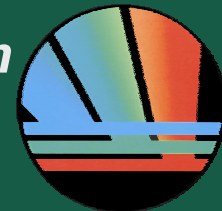




# ***ECD and United Solar PV Manufacturing R&D Program***

## ***Comprehensive On-Line Closed-Loop Diagnostic Systems***

### ***- Introduction -***



## ***Implementation of a Comprehensive On-Line Closed-Loop Diagnostic System for Roll-to-Roll Amorphous Silicon Solar Cell Production***

### ***Introduction***

- ECD and United Solar***
- ECD/United Roll-to-Roll Production Technology***
- Impact of NREL PV MaT/Man Funding***

### ***Summary of Phase I of the PV Man R&D 6 program***

***Task I: Implement Closed Loop Control of Film Thicknesses***

***Task II: Component Cell PVCD development – for use in future continuous online optimization***

***Task III: Plasma Diagnostics/Improved Deposition Technology***

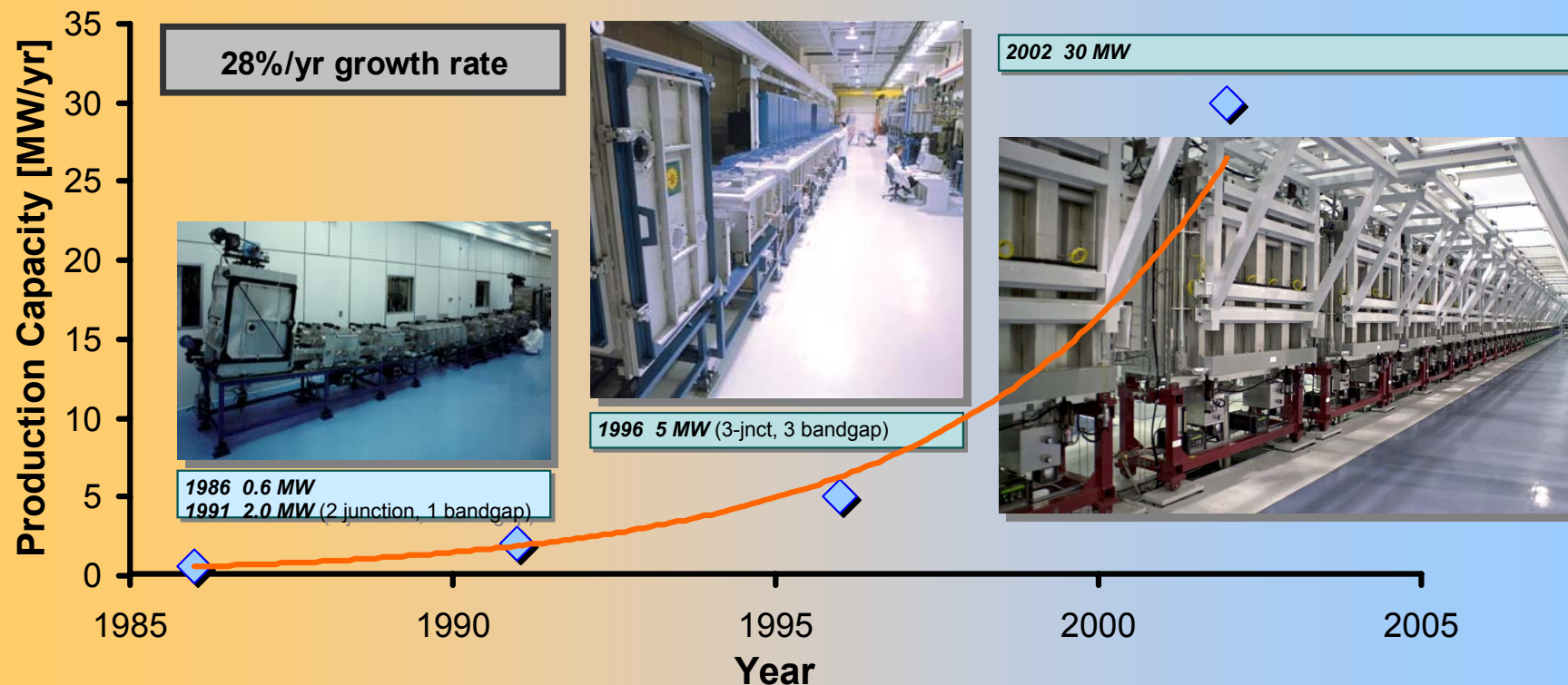
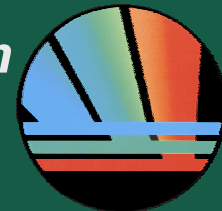
***Task IV: Yield Improvements: Substrate Cleaning – prove efficacy of plasma cleaning and get rid of washing machine***



# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

### -ECD/United Solar-



ECD/United Solar Joint Venture manufacturing capacity over the last 15 years. During this time capacity has expanded at about 30%/year, with more rapid expansion in the last 5 years.

*To see a World in a Grain of Sand  
And a Heaven in a Wild Flower  
Hold Infinity in the palm of your hand  
And Eternity in an hour*

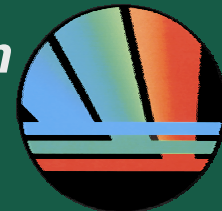
*William Blake, Auguries of Innocence*



# **ECD and United Solar PV Manufacturing R&D Program**

## **Comprehensive On-Line Closed-Loop Diagnostic Systems**

### **-ECD/United Solar-**



**New 30 MW Manufacturing Facility  
in Auburn Hills MI**

**January 03 – Production Mode**

**March 03 – 5 MW Production  
Facility shunt down**



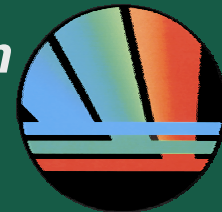




# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

### *-ECD/United Solar Production Technology-*



## Roll-to-Roll a-Si production Technology

### 4 Roll-to-Roll Machines:

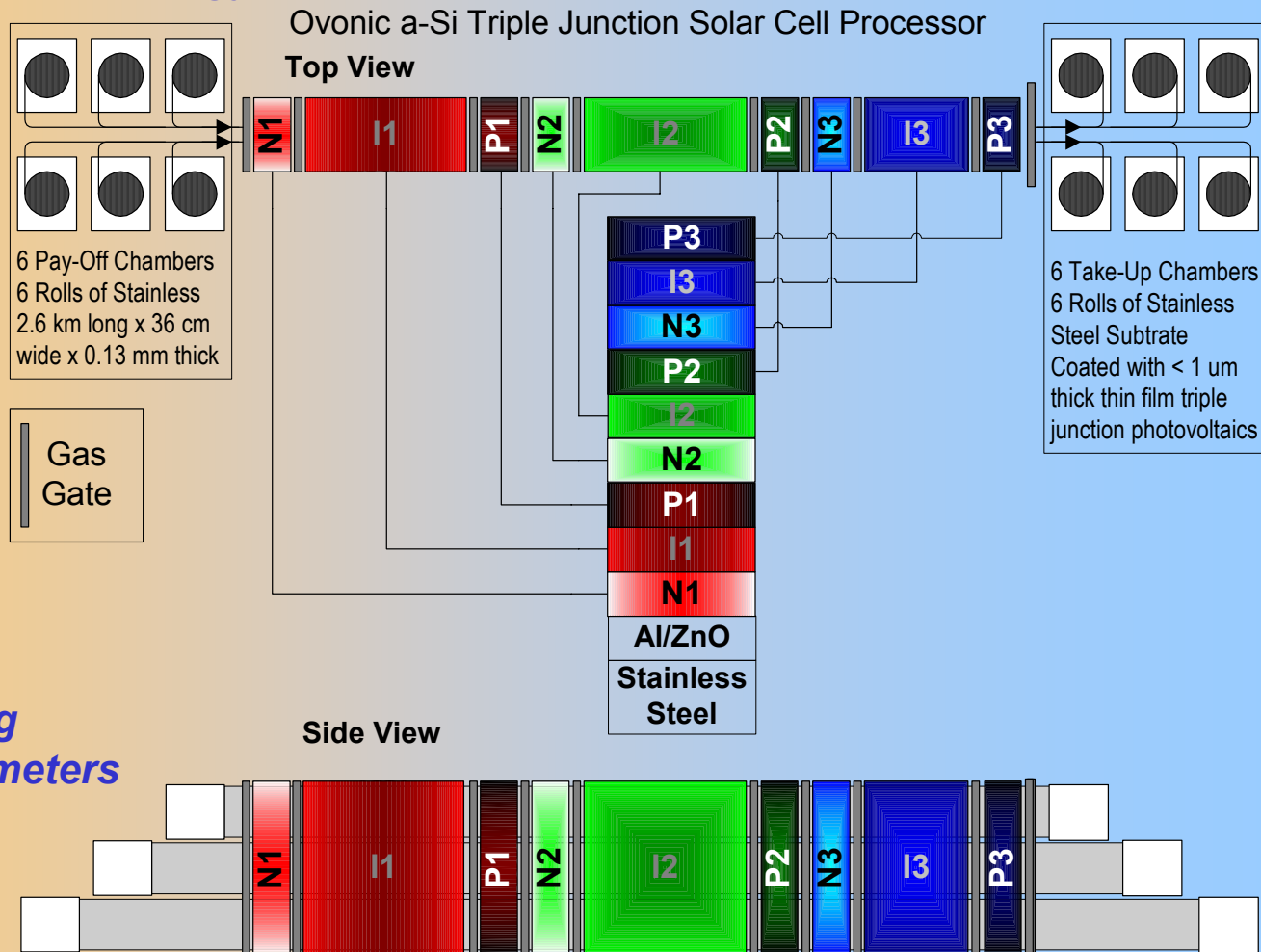
- Washing Machine (WM)
- Backreflector (BR)
- a-Si (30 MW)
- ITO Machine (ITO)

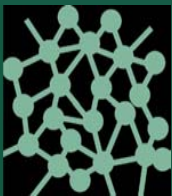
### 30 MW

- 6 x 2500 m rolls
- triple junction

### PV MaT 5A Technologies:

- New NiChrome Heaters
- New Cathode Design
- "Pinch" Valves
- Reactive ZnO Sputtering
- The PVCD and Spectrometers

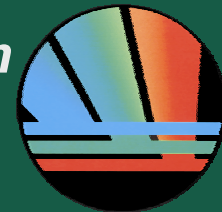




# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

### -United Solar BIPV Products-



*First metal roofing PV Installation [NAHB RC 21<sup>st</sup> Century Townhouse Project in Maryland]. DOE PV:BONUS Program.*

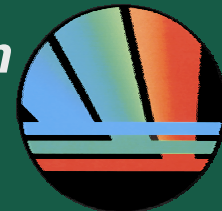


**Architecturally- and aesthetically-integrated Uni-Solar shingle (left) and metal-roofing BIPV installations made from lightweight, flexible, rugged a-Si thin film PV.**



# *ECD and United Solar PV Manufacturing R&D Program*

## *Comprehensive On-Line Closed-Loop Diagnostic Systems*



*Where have we come from?*

*Pre-PVMaT 5 – Windows in the Take-Up (TU) Chambers*

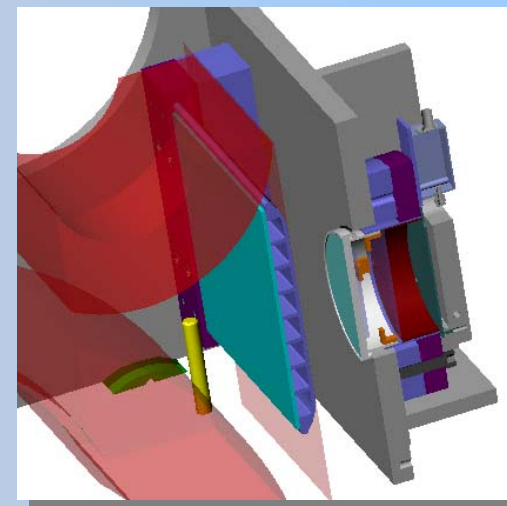
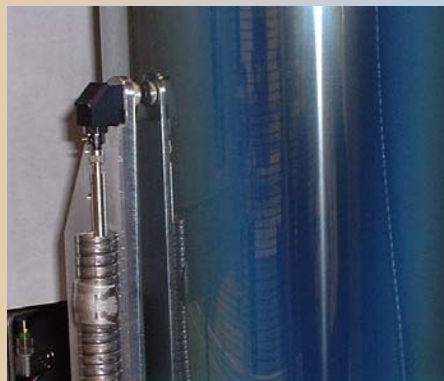


*Post-PVMaT 5 – 1 PVCD and 1 Spectrometer in 5 MW TU Chamber*  
*-- Limited QA; Some QC and Diagnostics*

*Development of New “Eyes”*

*Can “see”:*

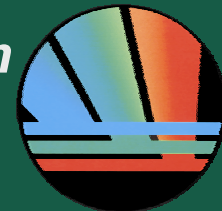
- Thickness*
- $V_{OC}$*
- $J_{SC}/C$ , ...*



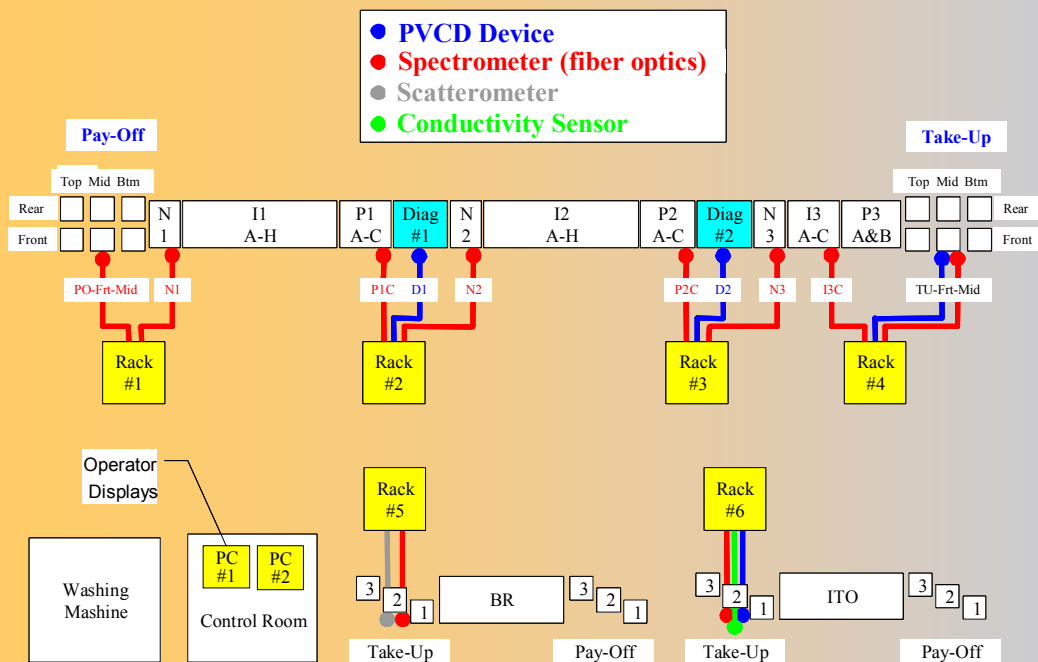


# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems



## PV Man R&D 6: Where are we going?



**Online Characterization**  
**Online QA/QC**  
**Developing:**  
**Closed-loop Thickness Control**  
**Continuous Online Optimization**

**~ 10 Networked Computer DAQ Systems**  
**10's of Diagnostic Systems**

Roll-to-Roll Processor	Diagnostic Systems	Number	Measurement
Washing Machine	Optically Stimulated Electron Emission (OSEE)	2	Cleanliness
Backreflector	Scatterometer	1	Specular and diffuse reflection
	Reflection Spectrometers	1	ZnO film thickness
30 MW a-Si	Reflection Spectrometers	8	Thickness of BR and each n-, i-, and p-layer
	PVCD	4	Component and device electrical properties
ITO	Film conductivity	1	ITO conductivity
	Reflection Spectrometers	5	ITO film thickness
	PVCD	1	Device electrical properties; degree of shunts prior to passivation.





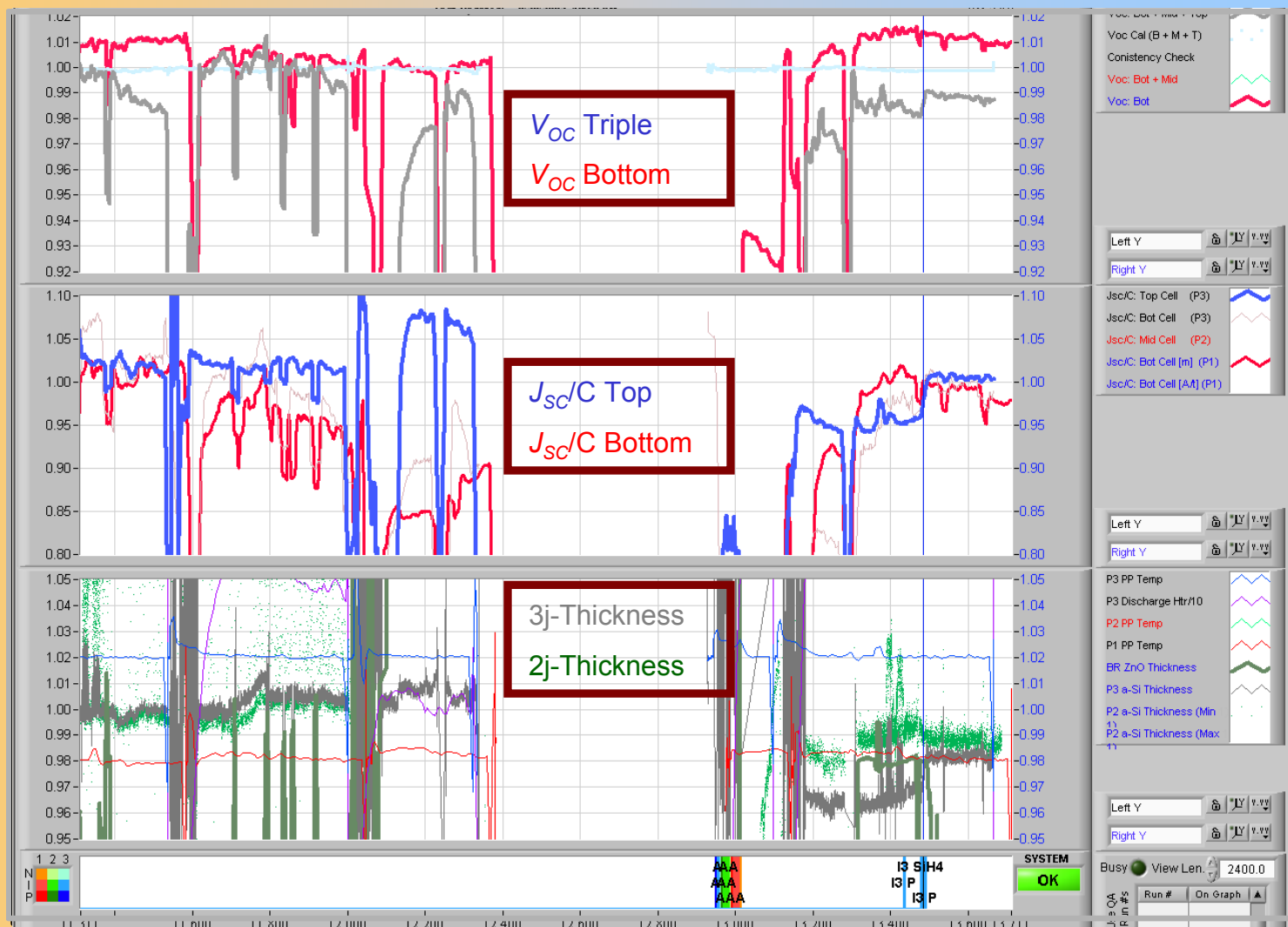
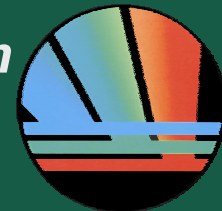


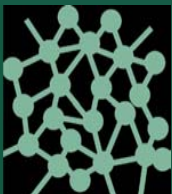


# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

### Success – What this Program is Yielding

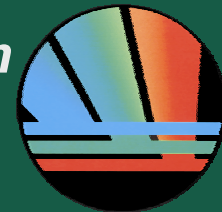




# *ECD and United Solar PV Manufacturing R&D Program*

## *Comprehensive On-Line Closed-Loop Diagnostic Systems*

### *A Whole New Regime*



#### *Questions –*

*The 30 MW has hundreds, if not thousands, of significant knobs. With 1-week turn-around of an experiment, how long would it take to completely optimize this machine?*

*How long to then optimize the 30 MW with the BR and ITO?*

#### *Think about this:*

*The R&D reactors can produce 1 – 3 samples/day, with poor statistics*

*With a complete online diagnostics systems we can perform hundreds of experiments/day 24/7 – with good statistics and no question about applicability to production.*

*How does one “automate” the experiment and experiment analysis process?*

*Can you symbiotically perform research on a production machine?*

*Production: Never change anything*

*Goal: make the exact same thing everyday*

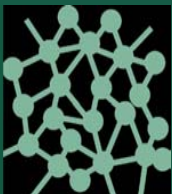
*R&D: **Constant** experimentation; change everything*

*Goal: all material above average*

*YES -- while we admit that the primary purpose of the machines may be production, we are demonstrating that simultaneous R&D can benefit production.*

*We have developed a very good working relationship with the production personnel*

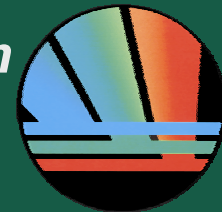
*-- this is the most significant breakthrough in production technology in the last 10 years.*



# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

### Program Overview



#### Work Areas:

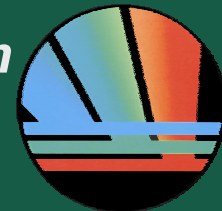
- 1. Closed Loop Thickness Control in the ITO, BR, and a-Si Machines**  
*Thickness measurement of all 9 layers in the triple junction a-Si device.*  
Phase I: Instrument BR, ITO, and a-Si TU; Second Generation a-Si Spectrometer  
Design ITO and BR Closed Loop Thickness Control System
- 2. Component Cell PVCD Development**  
 *$V_{OC}$ ,  $J_{SC}/C$  and other measurements of each cell in the triple junction device*  
*Implement Program of Continuous Online Optimization*  
Phase I: Design, Fabricate, Install, Retrofit 1<sup>st</sup> Component Cell PVCD
- 3. Plasma Diagnostics; Improving Deposition Hardware**  
Phase I: Install Diagnostics; Analyze Plasmas  
Study Particle Production in a-Si Machine
- 4. Yield Improvements – Substrate Cleaning**  
*Implement Plasma Cleaning – Eliminate 1 of 4 Roll-to-Roll Production Machines*  
Phase I: Online Cleanliness Diagnostic in WM  
Correlate cleaning parameters with yield  
Test plasma cleaning; compare with wet chemical cleaning  
Determine and address most significant sources of yield reduction





# ***ECD and United Solar PV Manufacturing R&D Program***

## ***Comprehensive On-Line Closed-Loop Diagnostic Systems***



### ***Task I: Closed Loop Thickness Control I***

#### **TASK 1: Develop Closed-Loop Control of Film Thickness**

-- Jeff Karn (ECD), Rujiang Liu and Jon Call (United Solar), Dave Dodge (Focus Software)

##### **Milestones**

- Complete M-1.0.1** Complete testing of 1st generation a-Si reflection spectrometer in production equipment.
- Complete M-1.1.1** Complete conceptual design of 1st generation ITO and ZnO closed-loop thickness-control systems.
- Complete M-1.2.1** Complete installation of 2nd generation a-Si reflection spectrometer in production equipment.
- Complete M-1.3.1** Complete fabrication of 1st generation closed-loop thickness-control systems for ITO and ZnO.
- Complete M-1.4.1** Complete the Phase I portion of the effort under Task 1.

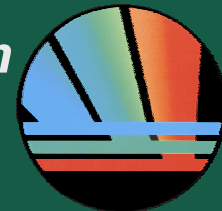
##### **Deliverables**

- Complete D-1.0.1** Report summarizing the testing of the 1st generation a-Si reflection spectrometer in the production equipment.
- Complete D-1.2.1** Report summarizing closed-loop thickness-control systems fabricated for the ITO and ZnO film thickness
- Complete D-1.3.1** ECD/United Solar confidential datalog display from a complete production roll of material demonstrating a-Si spectrometer thickness measurements



# ***ECD and United Solar PV Manufacturing R&D Program***

## ***Comprehensive On-Line Closed-Loop Diagnostic Systems***



### ***Task I: Closed Loop Thickness Control I***

#### Overview

#### First Generation a-Si Spectrometer

- Hardware

- Reflection Spectra

- Software

  - Online DAQ

  - Online Operator Interface

  - Offline Analysis Utilities

- Stop and Burn Technology (Unplanned Benefit)**

  - Trouble-shooting

  - Integrals – motivation for 2<sup>nd</sup> Generation a-Si Spectrometer

#### Second Generation a-Si Spectrometer

- Design (actually, this is second design – Needed the “A” team)

- First Operation

#### Closed Loop Thickness Control System (BR)

- Spectra

- “Manual” Looping; Motivation (stabilize process by stabilizing input)

- System Design – looks straightforward ... (don't quote me on that)

#### ITO –

- More Difficult than Initially Thought**

  - Color**

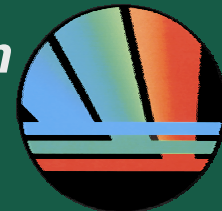
  - Need to stabilize a-Si input!***



# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

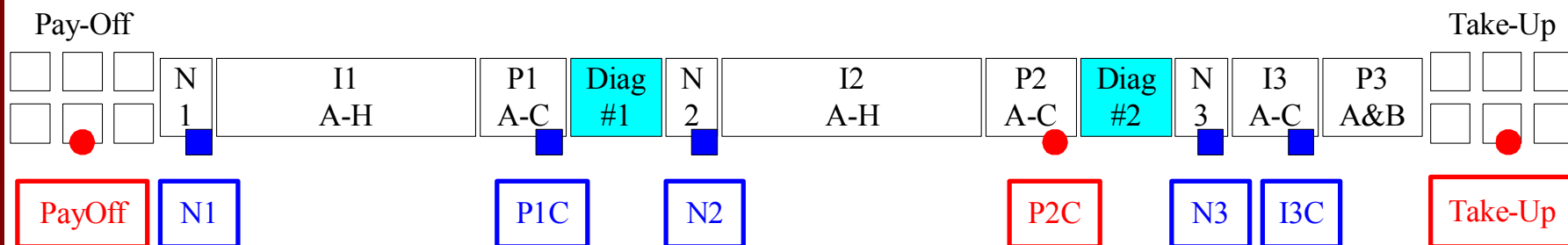
### Task I: Closed Loop Thickness Control I



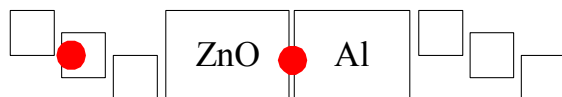
#### Overview

- Operational Spectrometers
- Future Spectrometers

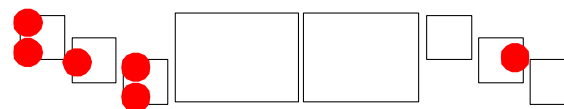
30 MW Machine (all spectrometers on Front-Middle web)



BR Machine



ITO Machine



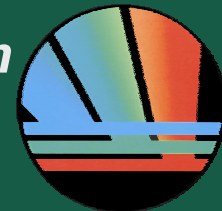




# ECD and United Solar PV Manufacturing R&D Program

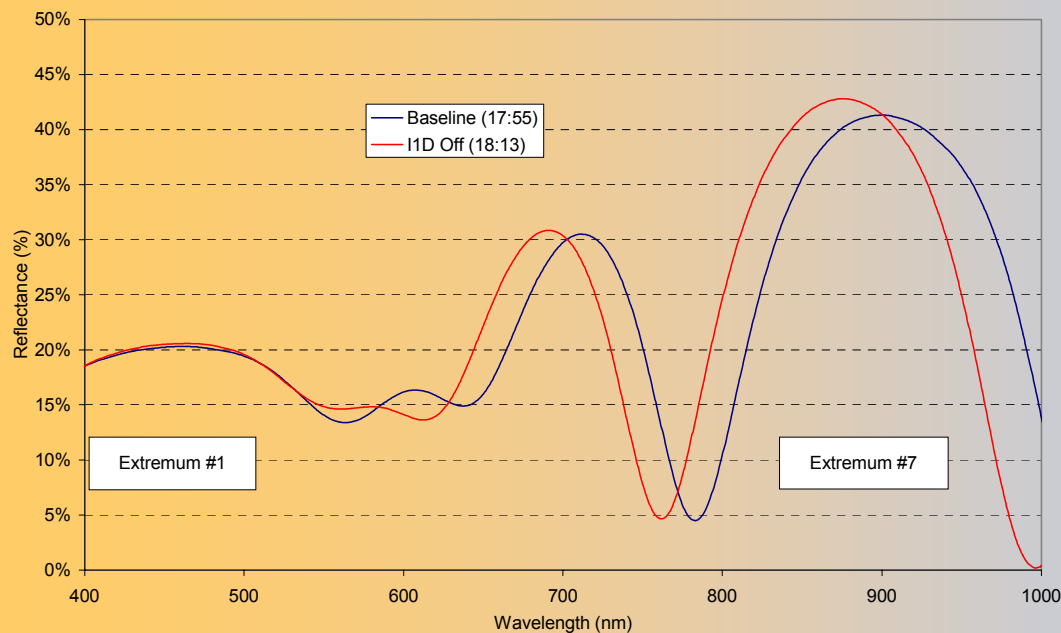
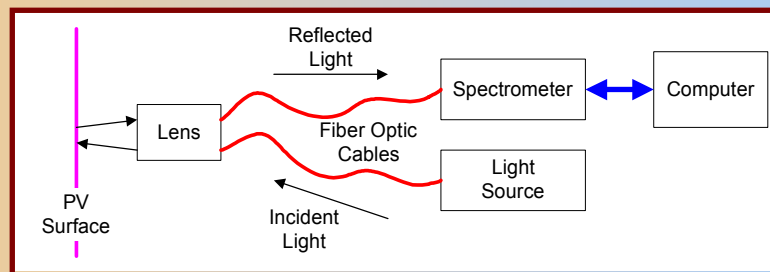
## Comprehensive On-Line Closed-Loop Diagnostic Systems

### Task I: Closed Loop Thickness Control I



#### Overview

Hardware and  
Typical Spectra

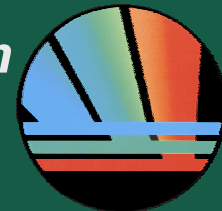




# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

### Task I: Closed Loop Thickness Control I

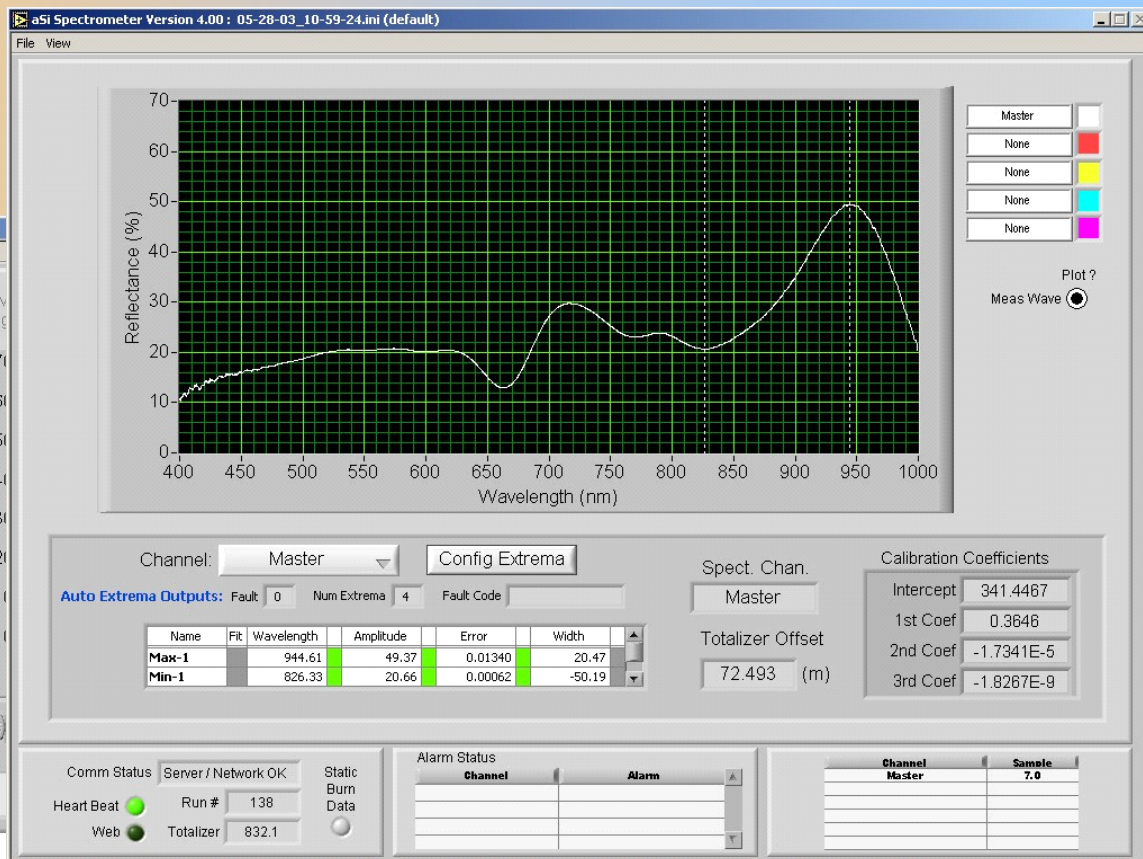
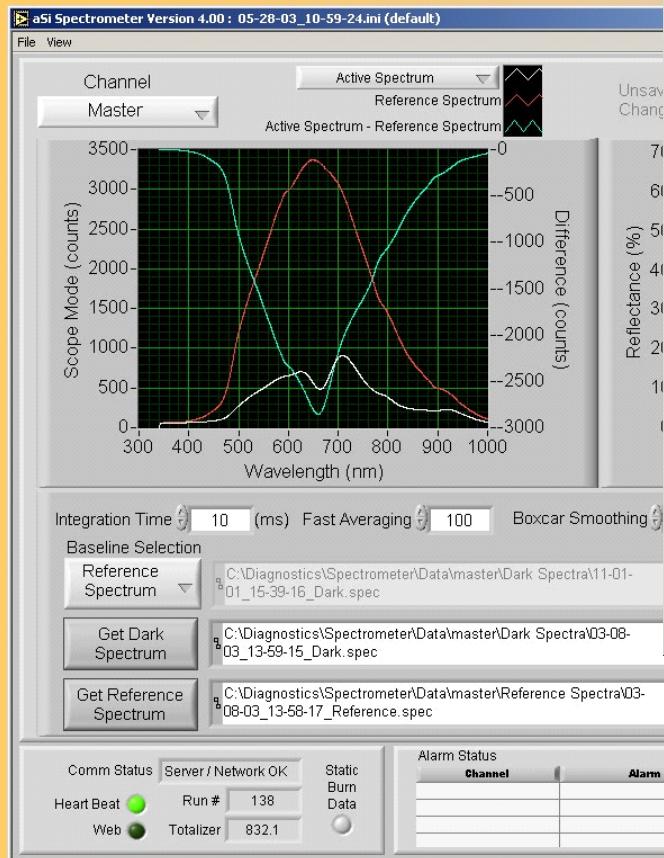


#### Software –

Online DAQ

Online Operator

Offline Analysis Utilities



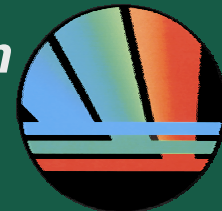
Expert and Details “Panels”

Tim Ellison, Ph.D.  
Energy Conversion Devices, Inc.



# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems



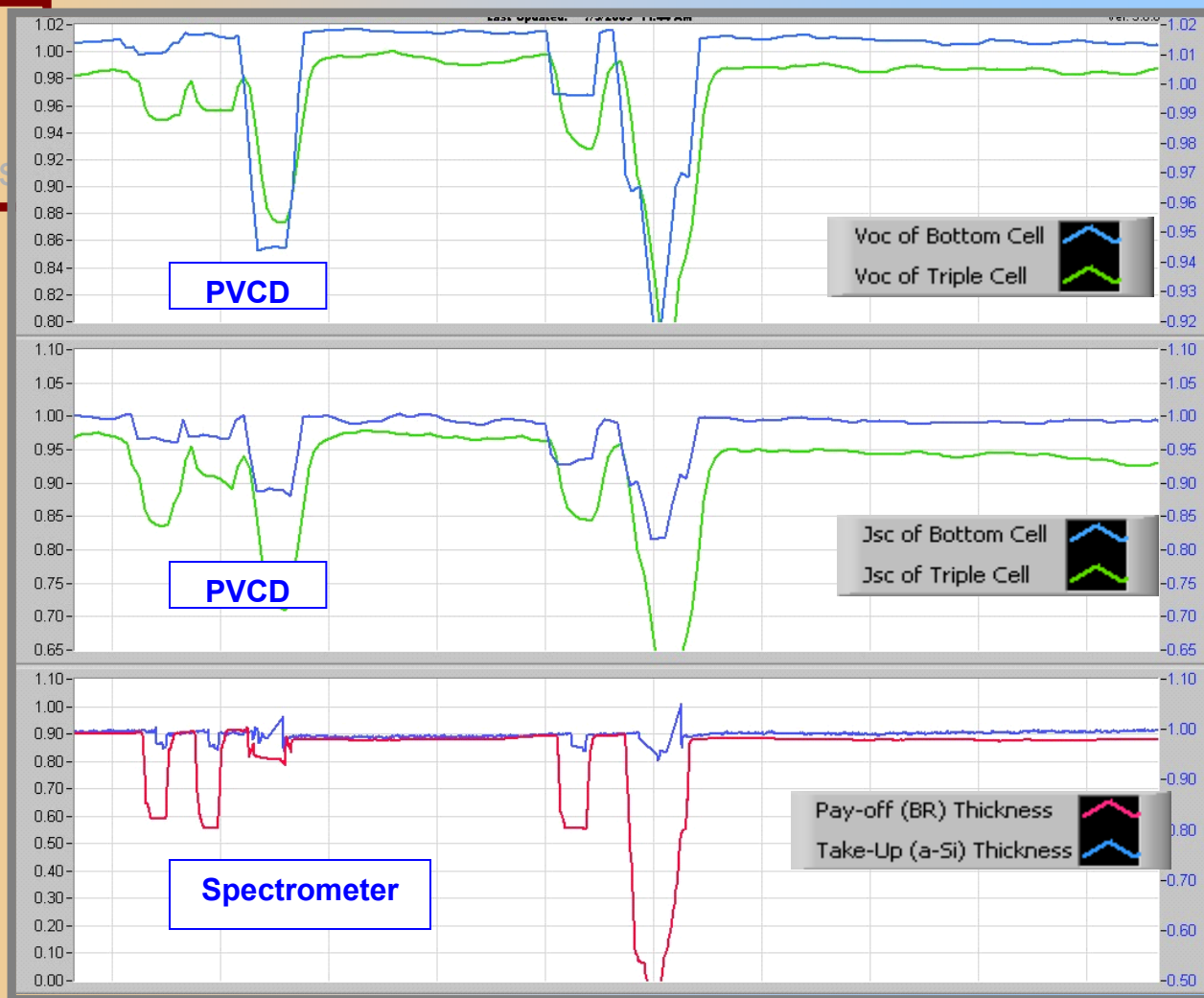
### Task I: Closed Loop Thickness Control I

#### Software –

Online DAQ

Online Operator

Offline Analysis Utilities



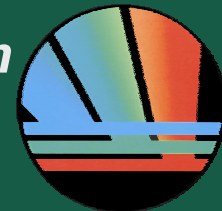




# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

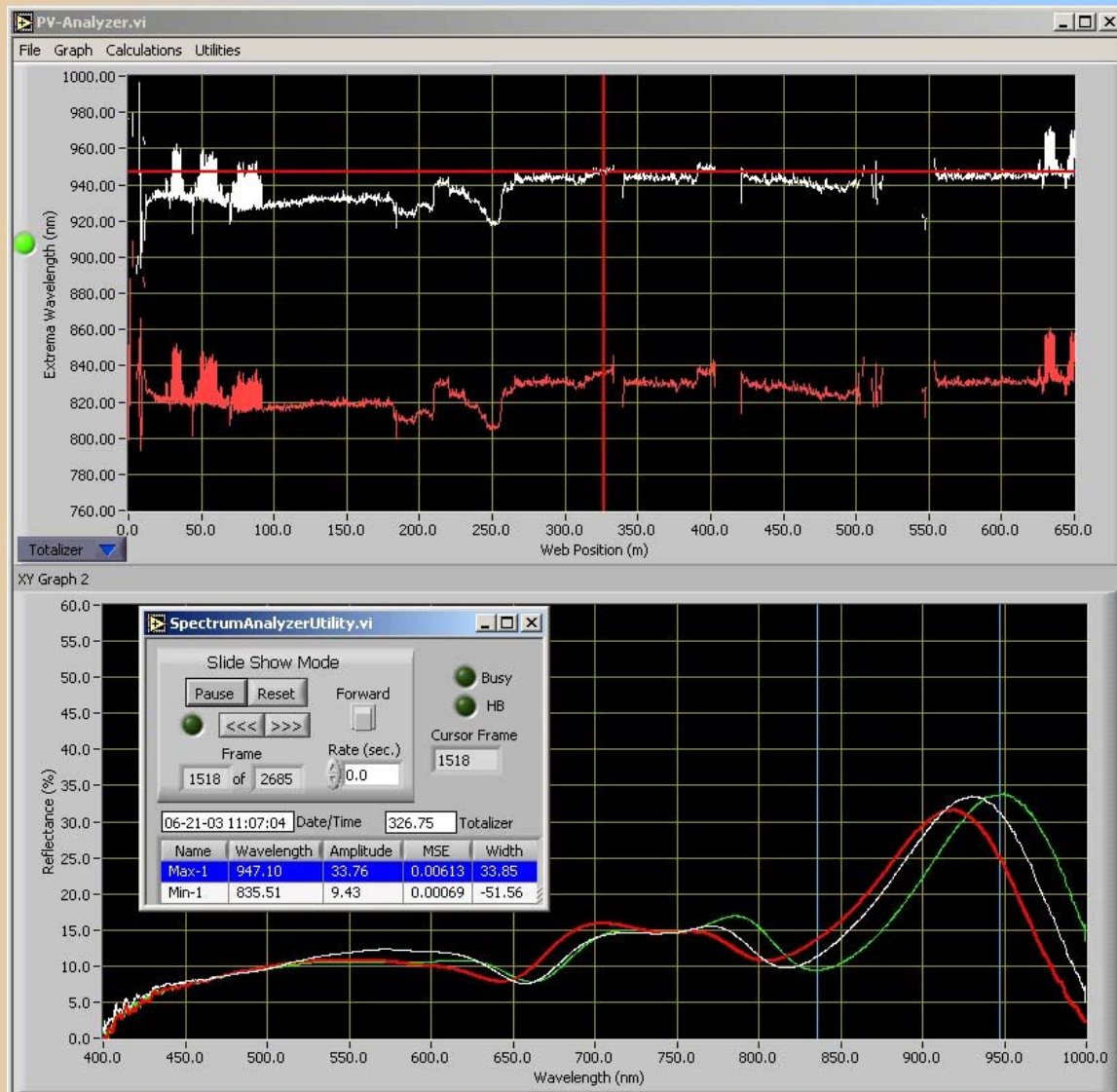
### Task I: Closed Loop Thickness Control I



#### Software –

- Online DAQ
- Online Operator
- Offline Analysis Utilities

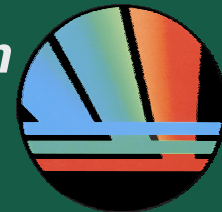
*Raw Data (Spectra) are saved and archived so that old “Runs” can be played back to optimize fitting algorithms*





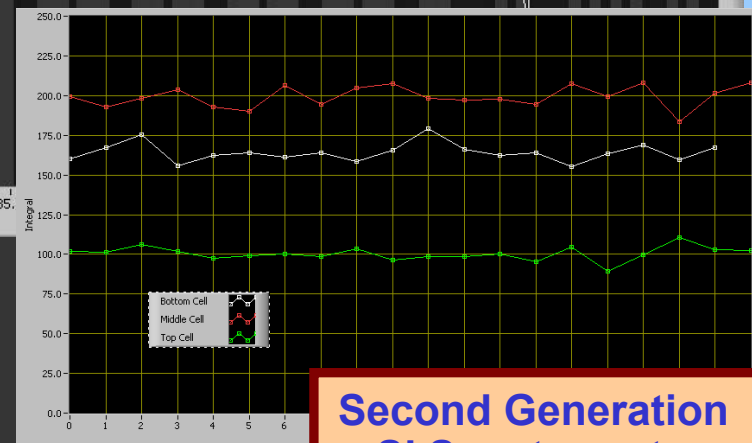
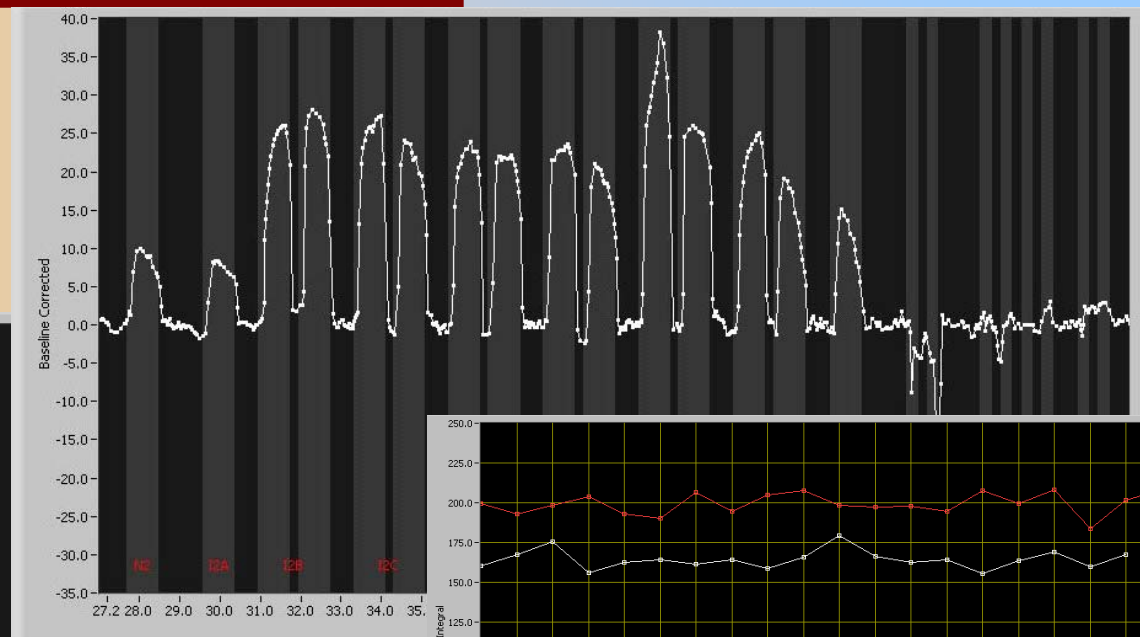
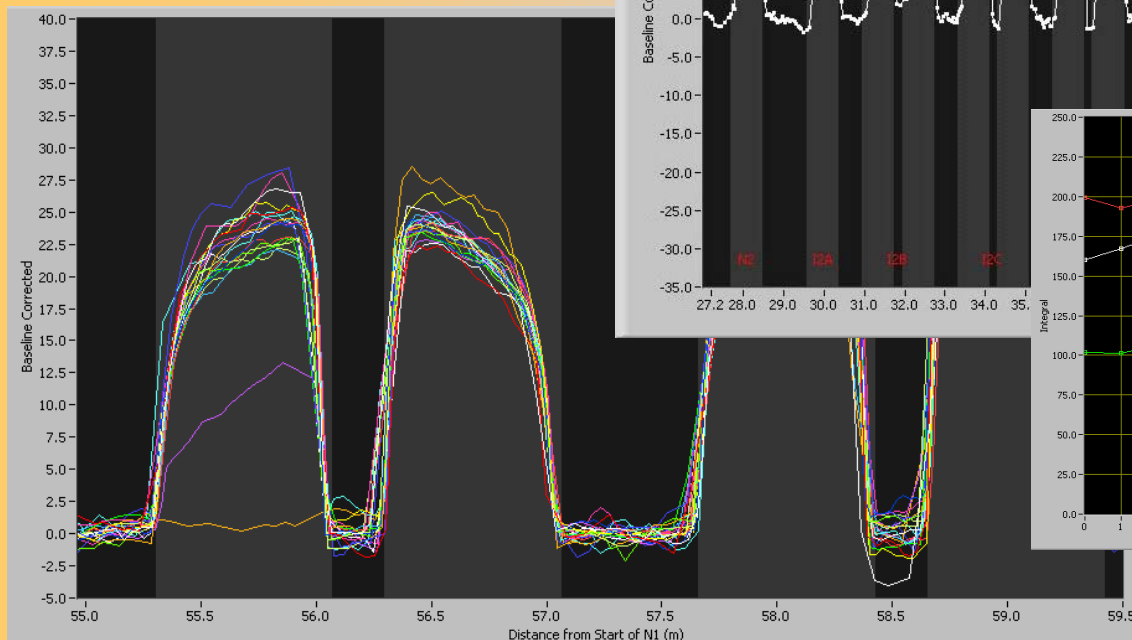
# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems



### Task I: Closed Loop Thickness Control I

#### "1-min On-the-Fly Static Burn" Technology – Bonus!

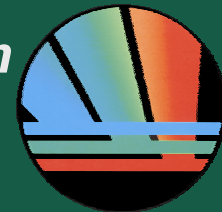


**Second Generation  
a-Si Spectrometer  
Motivation**



# **ECD and United Solar PV Manufacturing R&D Program**

## **Comprehensive On-Line Closed-Loop Diagnostic Systems**



### **Task I: Closed Loop Thickness Control I**

#### **Second Generation a-Si Spectrometer**

Design (really second design – Needed the “A” Team)

- 300 °C Temperatures
- Thermal Cycling
- UHV Compatible
- Avoid a-Si deposition on spectrometer optics
- Moving web must be free from vibration or angular changes
- Located inside a long narrow region between webs
- Hidden from visual inspection, hands-on adjustment



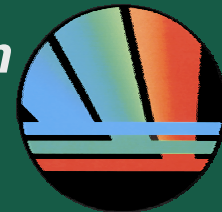




# ECD and United Solar PV Manufacturing R&D Program

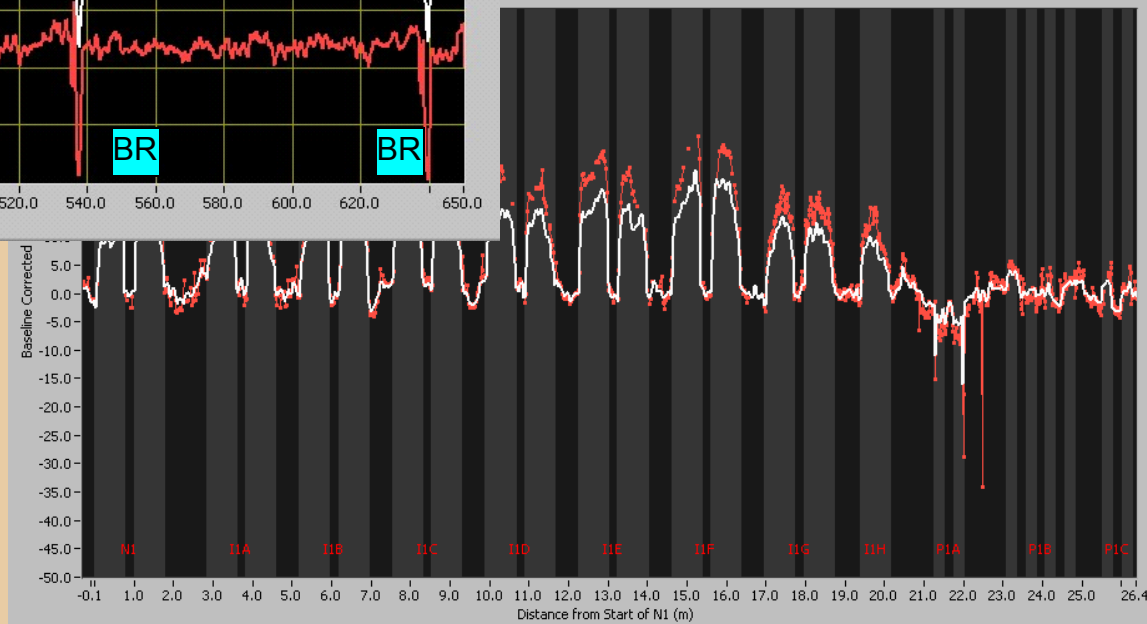
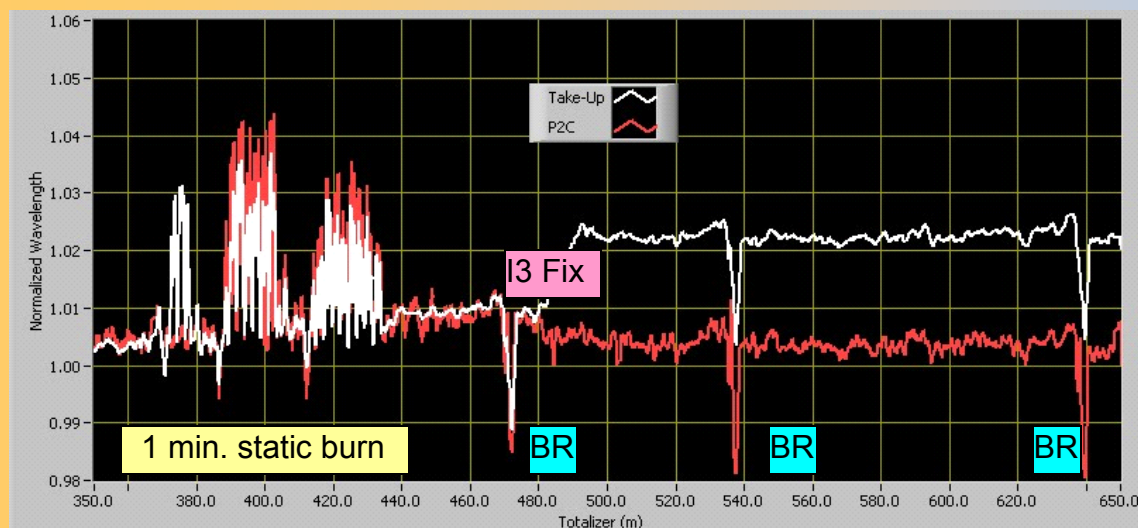
## Comprehensive On-Line Closed-Loop Diagnostic Systems

### Task I: Closed Loop Thickness Control I



## Second Generation a-Si Spectrometer

### First Operation

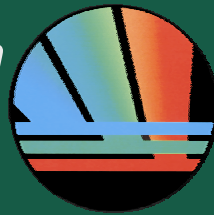




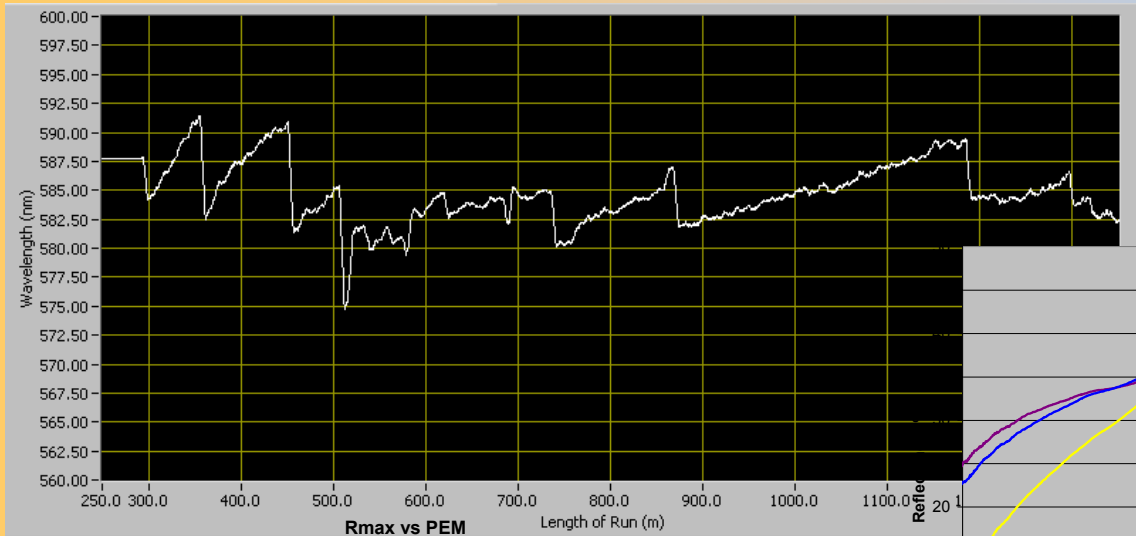
# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

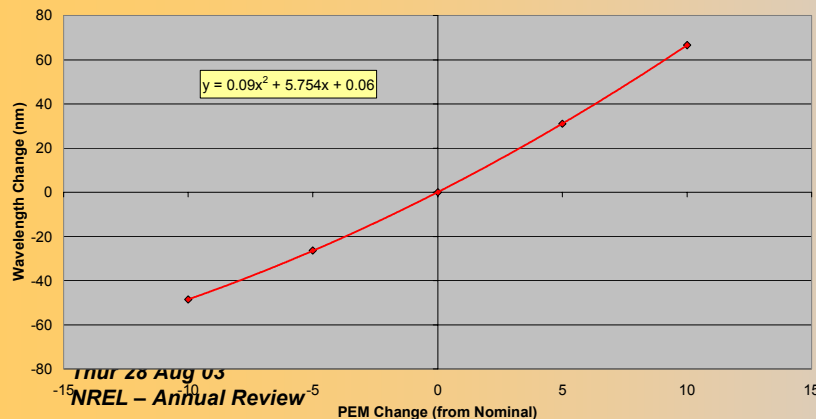
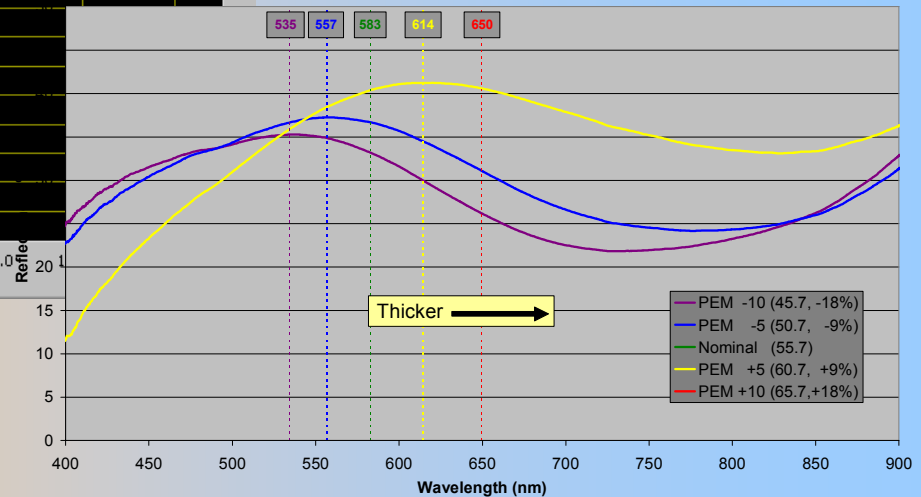
### Task I: Closed Loop Thickness Control I



Closed Loop Thickness Control System (BR) (ITO is a can of worms!)  
Presently humans close the loop –



BR Thickness Sensitivity to PEM Changes  
(30BR-104, 06-17-03)

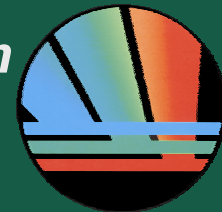




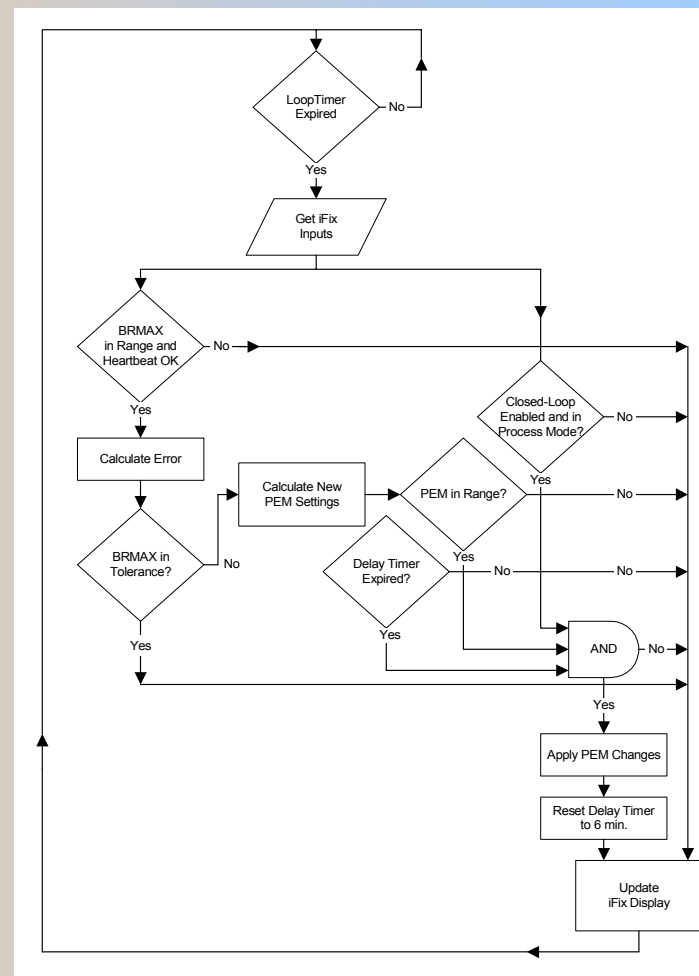
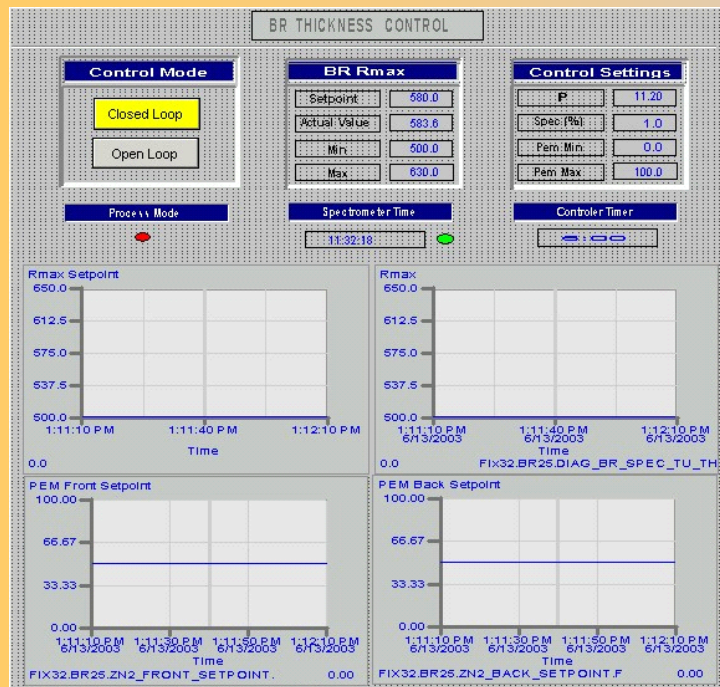
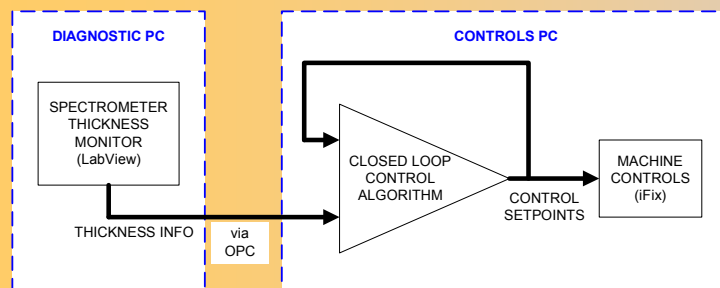
# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

### Task I: Closed Loop Thickness Control I



Closed Loop Thickness Control System (BR) (ITO is a can of worms!)  
System Design – “Conceptually Simple” – the exceptions are what will get us

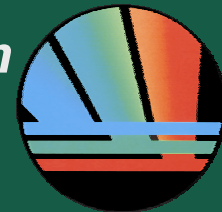




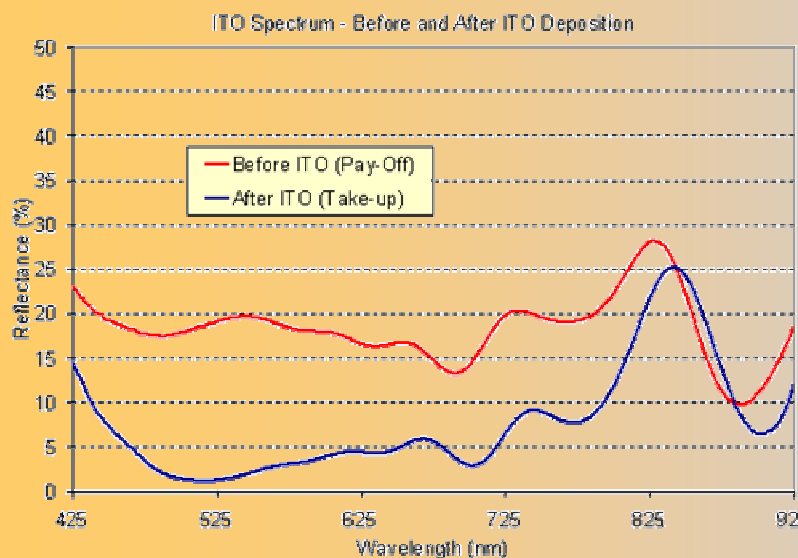
# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

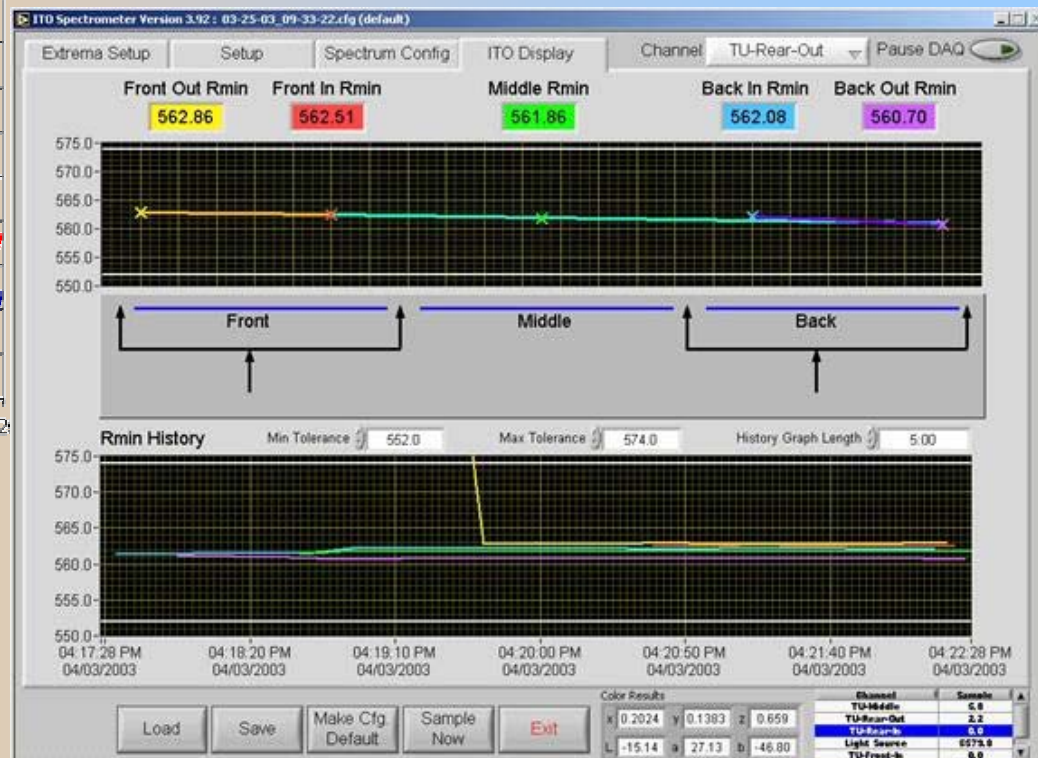
### Task I: Closed Loop Thickness Control I



Closed Loop Thickness Control System  
ITO not conceptually simple --



Color more important than thickness

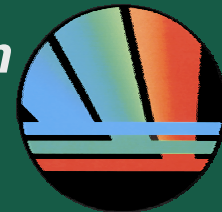






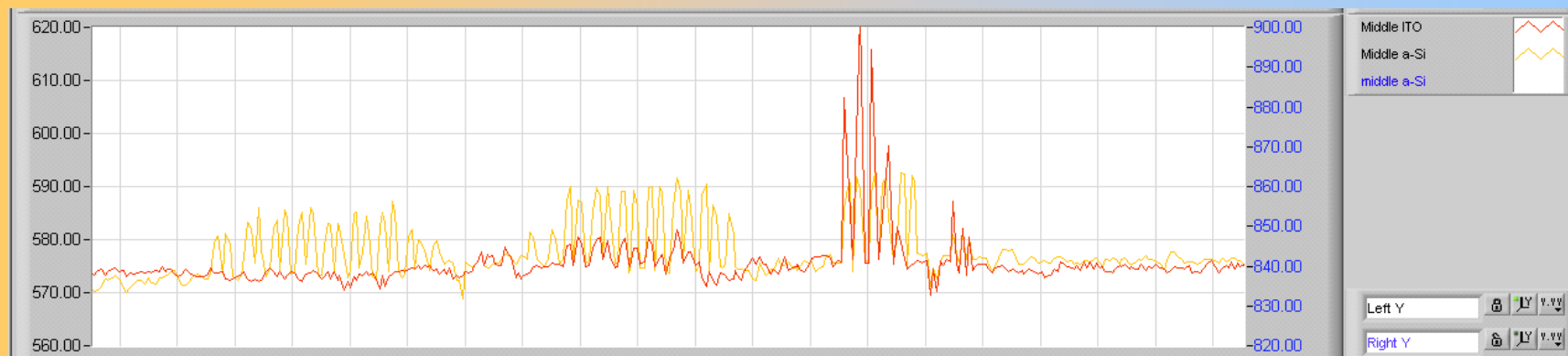
# **ECD and United Solar PV Manufacturing R&D Program**

## **Comprehensive On-Line Closed-Loop Diagnostic Systems**



### **Task I: Closed Loop Thickness Control I**

Closed Loop Thickness Control System  
ITO not conceptually simple --



Top Layer a-Si thickness affects reflection spectrum, and consequently color  
Best way to control output is to control input

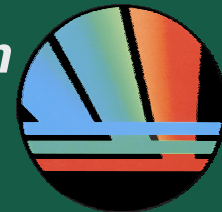
While we had initially thought controlling a-Si thicknesses was beyond the scope of this program, we are now more highly motivated

Will try, initially manually, closing the loop on a-Si top cell thickness before closing the loop on ITO thickness (color).



# ***ECD and United Solar PV Manufacturing R&D Program***

## ***Comprehensive On-Line Closed-Loop Diagnostic Systems***



### ***Task 2: Component Cell PVCD***

## **TASK 2: PV Capacitive Diagnostic Design and Fabrication for Bottom and Middle Cells**

– Tim Ellison, Rob Kopf and Wayne Messing (ECD); Dave Dodge (Focus Software)

### **Milestones**

- |                 |                |  |
|-----------------|----------------|--|
| <b>Complete</b> | <b>m-1.0.2</b> | <b>Complete initial bench testing of component cell PVCD.</b>  |
| <b>Complete</b> | <b>m-1.0.3</b> | <b>Complete bench testing of component high intensity LED light source and light source power supply.</b>    |
| <b>Complete</b> | <b>m-1.1.2</b> | <b>Complete preliminary testing of component cell PVCD in production machine.</b>                            |
| <b>Complete</b> | <b>m-1.3.2</b> | <b>Complete installation of retrofitted component cell PV Capacitive Diagnostic in production equipment.</b> |
| <b>Complete</b> | <b>m-1.4.2</b> | <b>Complete the Phase I portion of the effort under Task 2.</b>  |

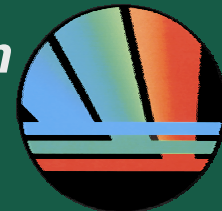
### **Deliverables**

- |                 |                |   |
|-----------------|----------------|---|
| <b>Complete</b> | <b>D-1.0.1</b> | <b>Report summarizing bench testing of high intensity LED light source and light source power supply</b>              |
| <b>Complete</b> | <b>D-1.1.1</b> | <b>Report summarizing design and installation of component cell PV Capacitive Diagnostic in production equipment.</b> |



# ***ECD and United Solar PV Manufacturing R&D Program***

## ***Comprehensive On-Line Closed-Loop Diagnostic Systems***



### ***Task 2: Component Cell PVCD***

#### **Component Cell PVCD:**

#### **Design, Fabrication, Testing, Installation, Optimization**

Background – PV MaT 5A Development

Motivation

Design

Challenges

Shutter System

Design Summary

Light Source

Installation (x3)

Optimization

First Operation/Noise

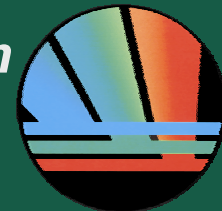
Plasma Noise Killer

Summary



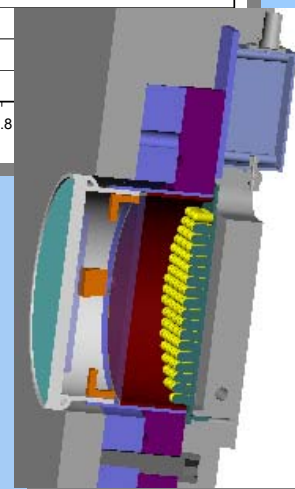
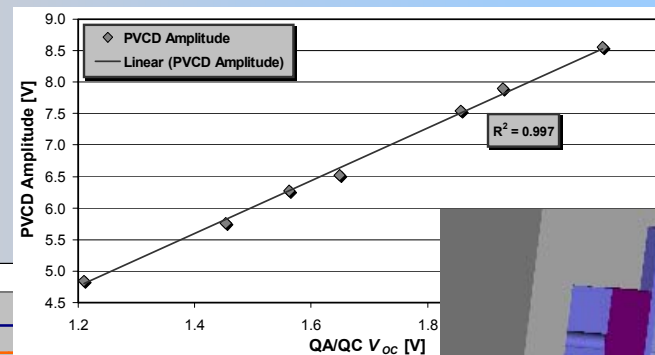
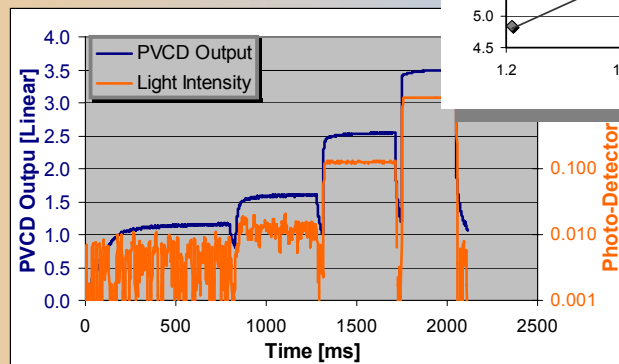
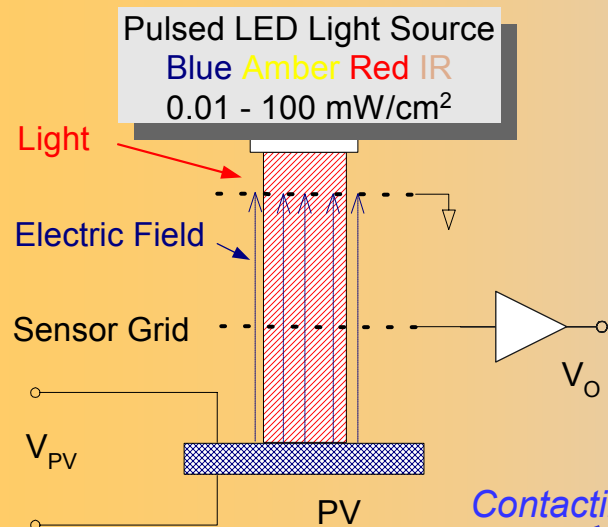
# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

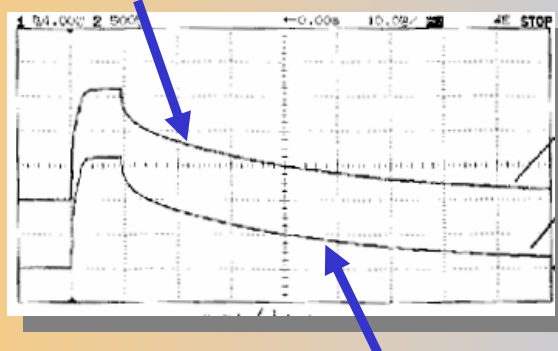


### Task 2: Component Cell PVCD

#### Component Cell PVCD: Background – PV MaT 5A



#### Contacting Measurement



#### Non-Contacting PVCD Measurement

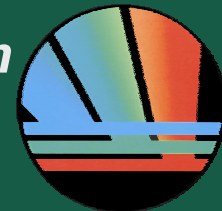
> 10 Independent Parameters in PVCD Waveform – 2 trivial and well established:  
Amplitude:  $V_{OC}$   
Initial Derivative:  $J_{SC}/C$





# ***ECD and United Solar PV Manufacturing R&D Program***

## ***Comprehensive On-Line Closed-Loop Diagnostic Systems***



### ***Task 2: Component Cell PVCD***

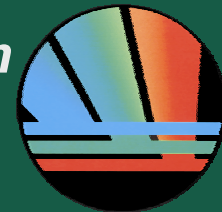
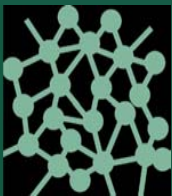
#### **Motivation –**

Unambiguous  $V_{OC}$ ,  $J_{SC}/C$ , and ? measurements for each component cell

- Pinpoint Problems – especially when combined with other diagnostics data (e.g. spectrometers)
- Significant Step Forward –

Data not available till now, even in offline testing

Together with Spectrometers, this system will allow us to embark on a serious program of Continuous Online Optimization – the ultimate goal of this work



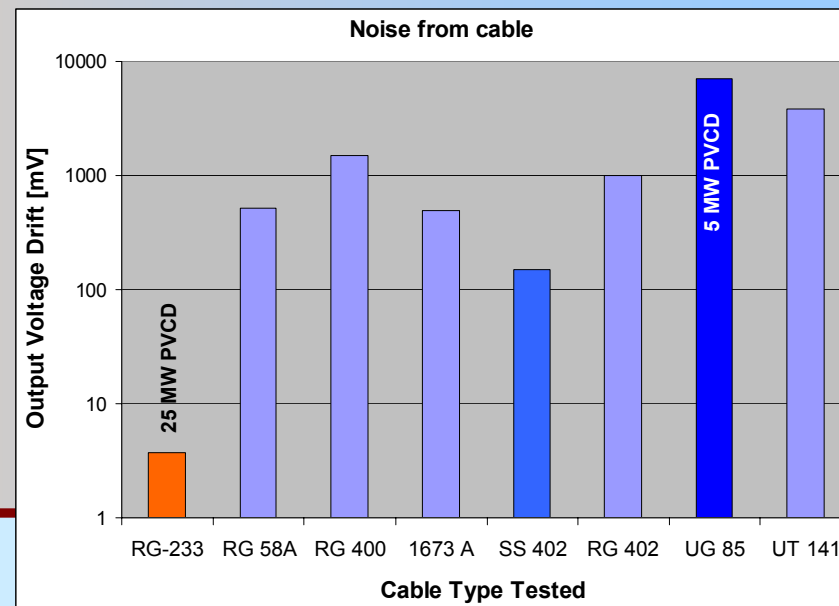
### Task 2: Component Cell PVCD

#### Design

Challenges  
Shutter System  
Design Summary  
Light Source

#### Challenges

Go from a few feet to a few inches --  
(Discharge Heater, Pre-cooler, Pusher Plate, PVCD)  
No access for calibration, viewing, testing, service  
Go from “dirty” to UHV-compatible  
(Electronics, cables, ...)  
Temperature Stabilization (0.1 °C)  
Sensor-to-web position stabilization (0.001” for 0.25%)  
EMI –  
(rf, plasma, heaters, ionized gas ...)  
Long cables

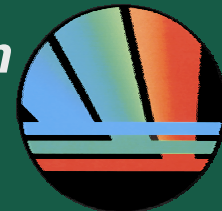


Accomplished with Shutter  
Measure “web offset voltage”  
Apply calibration signals

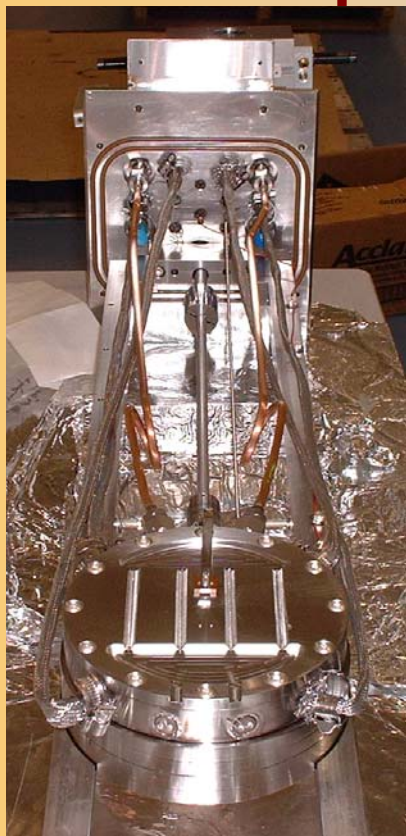
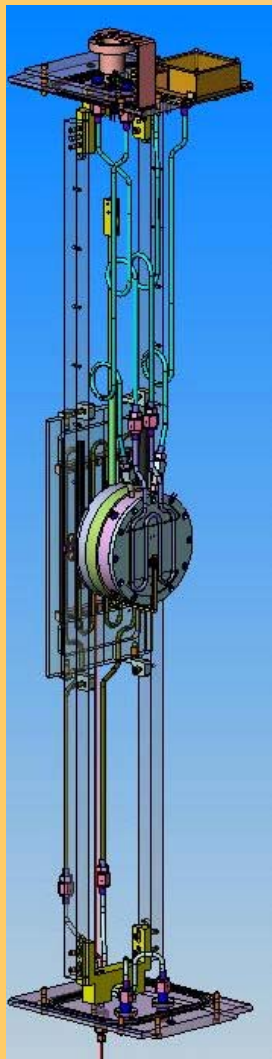


# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

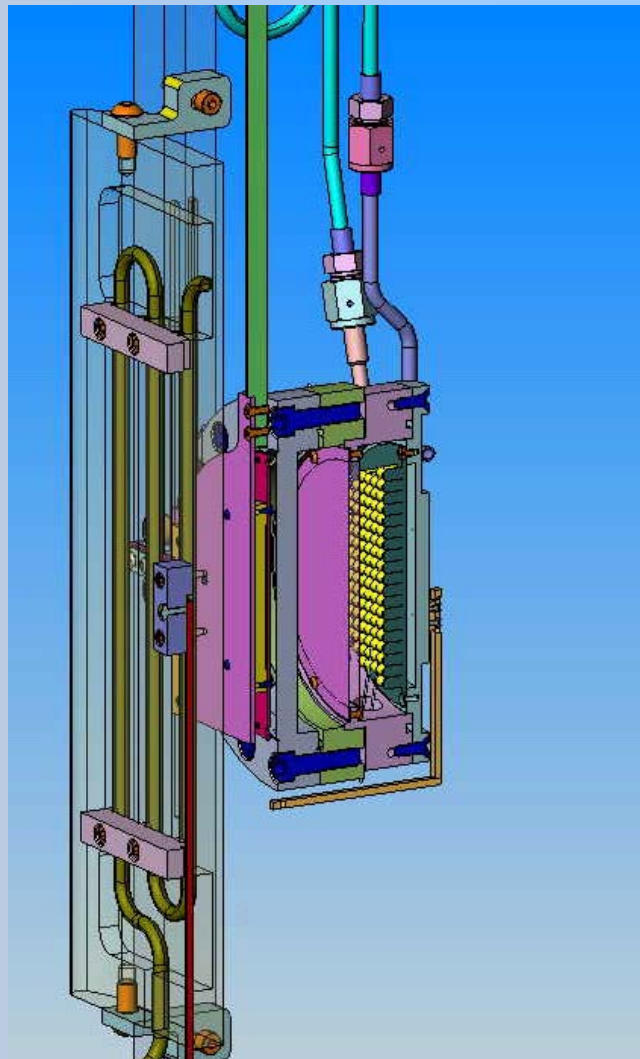


### Task 2: Component Cell PVCD



#### Design

Challenges  
Shutter System  
Design Summary  
Light Source



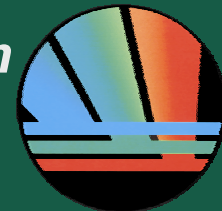
Thur 28 Aug 03  
NREL – Annual Review

Tim Ellison, Ph.D.  
Energy Conversion Devices, Inc.



# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

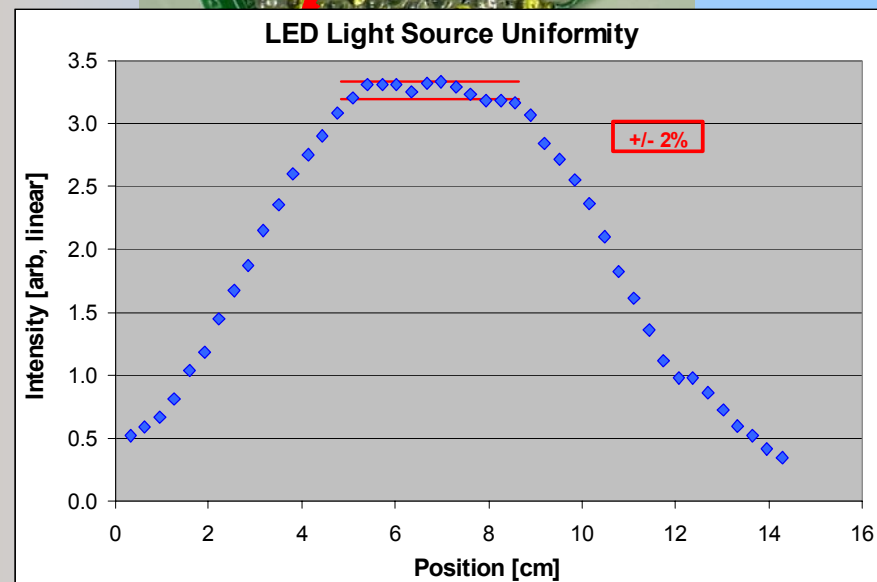
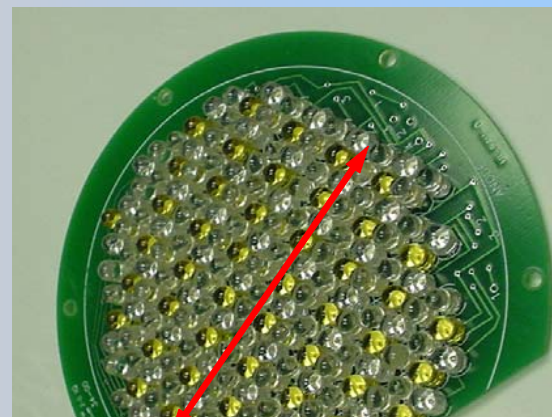
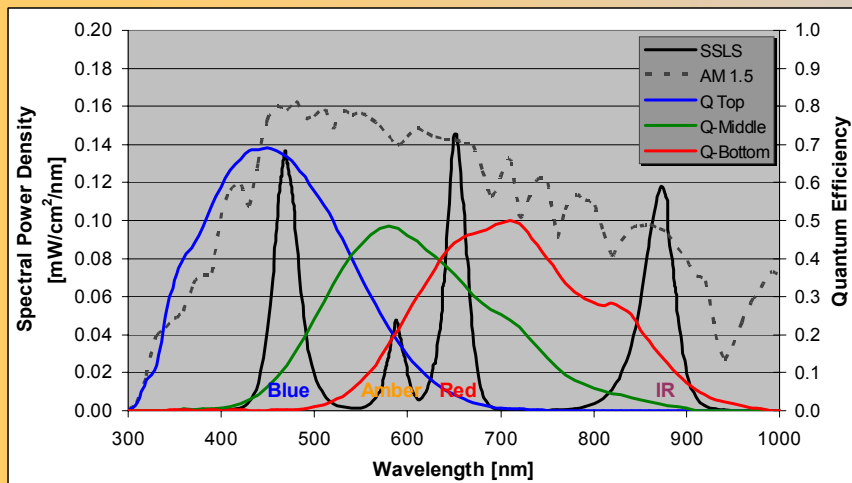


### Task 2: Component Cell PVCD

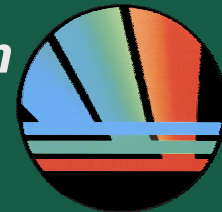
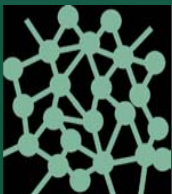
#### Design

Challenges  
Shutter System  
Design Summary  
Light Source

LED	Wavelength [nm]	Absorption Top	Middle	Bottom
Blue	474	1.00	0.19	0.01
Amber	588	0.41	1.00	0.42
Red	652	0.09	0.78	1.00
IR	860	0.00	0.13	1.00







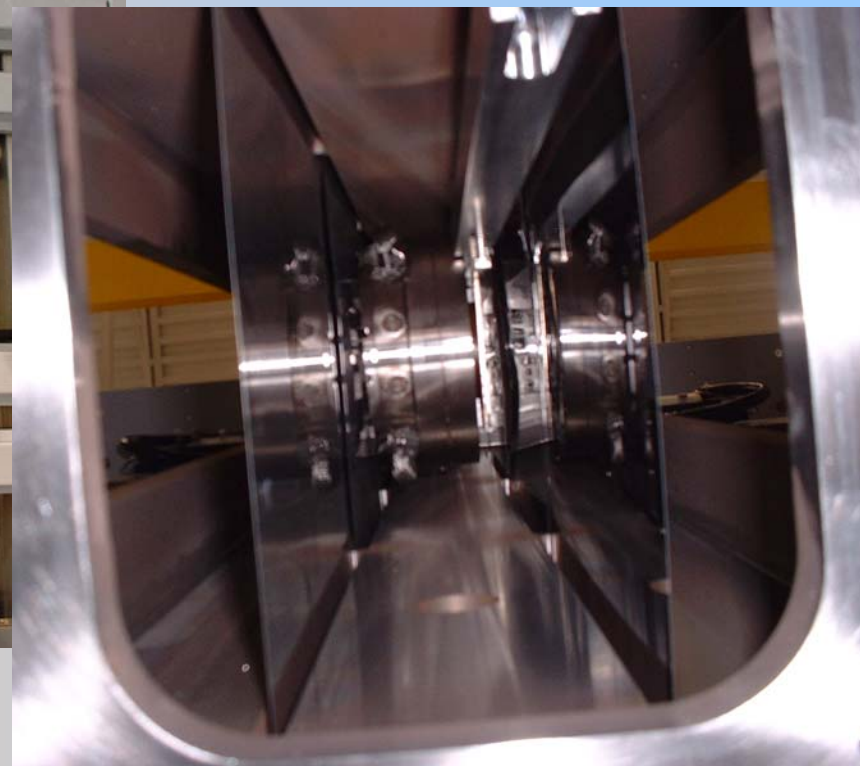
### Task 2: Component Cell PVCD

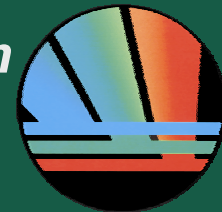
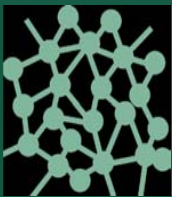
#### Component Cell PVCD: Installation (x3)



The Old “Ship-in-the-Bottle” Trick  
Improvements:

- Notch I-Beams
- More robust feedthroughs and electrical connections
- Better “Pusher Plate” coatings





### Task 2: Component Cell PVCD

#### Optimization

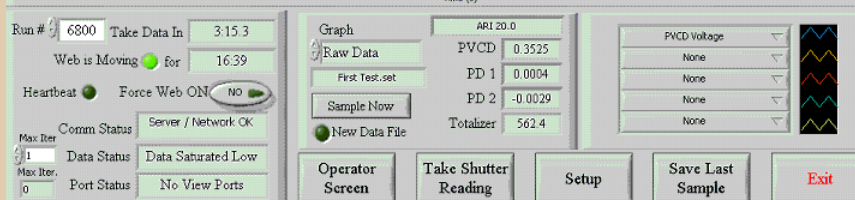
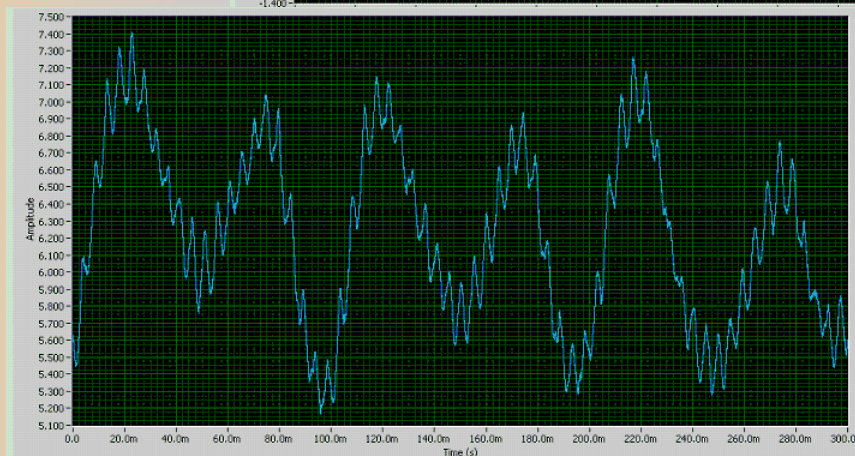
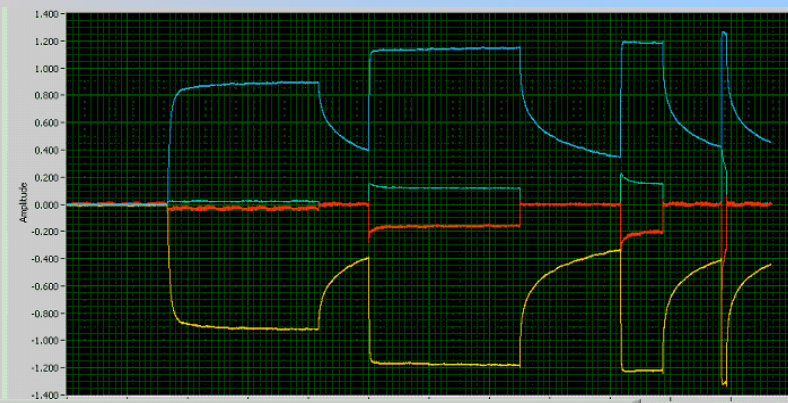
First Operation/Noise  
Plasma Noise Killer

Operated splendidly with plasma's  
and heaters off

With system operating, signal-to-  
noise ratio (S/N)  $\approx 0.5$

Was not clear that the system  
would work

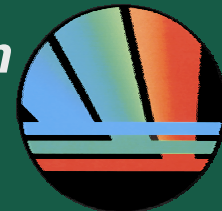
*Note – this plasma noise signal  
may turn out to be a useful  
diagnostic system –*





# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems



### Task 2: Component Cell PVCD

#### Optimization

First Operation/Noise  
Plasma Noise Killer

Averaging

Line-sinking

“Improbability Filter”

Subtracting initial baseline

Analytical waveform fitting

Post-filtering of waveform parameters

$S/N \approx 20$  (100 X)

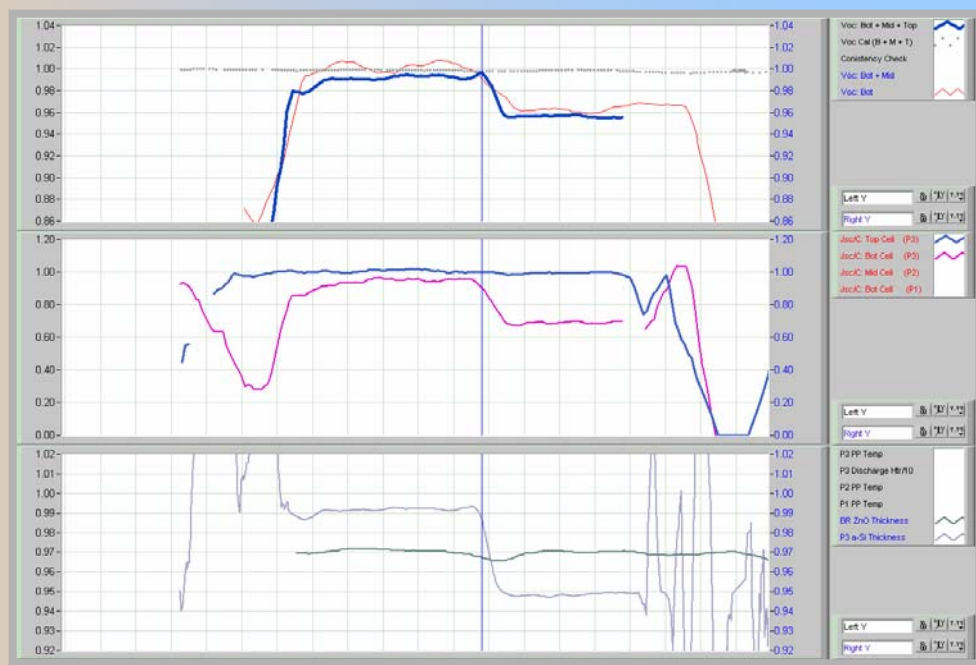
Note: Filtering/Averaging reaches point  
of diminishing returns –

$S/N \sim 1/\sqrt{\text{\#samples}}$

Did provide useful information

But too slow ...

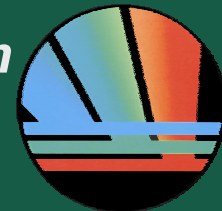
Too noisy for future online  
optimization







# ECD and United Solar PV Manufacturing R&D Program Comprehensive On-Line Closed-Loop Diagnostic Systems

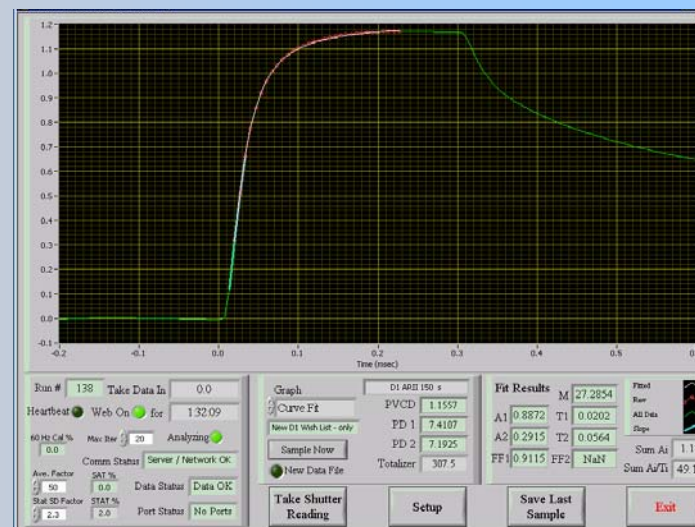
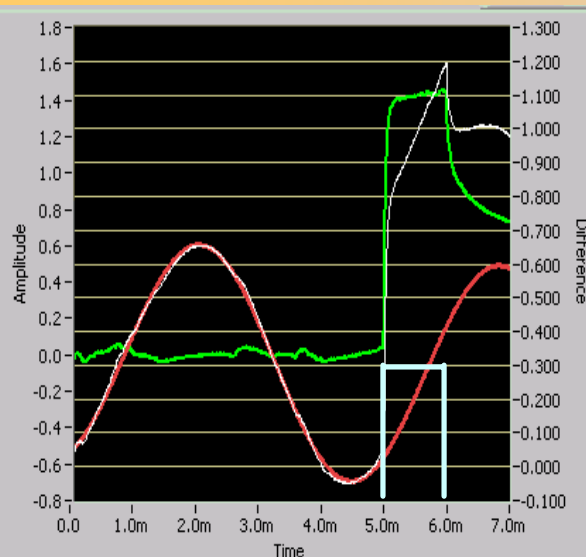


## Task 2: Component Cell PVCD

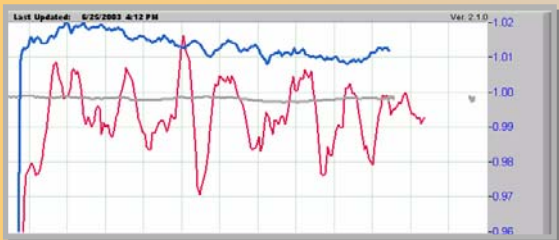
### Optimization

First Operation/Noise  
Plasma Noise Killer

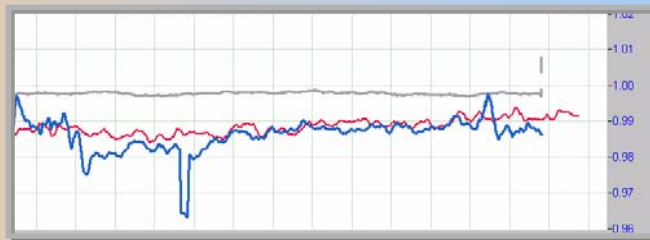
S/N now almost 1000  
Perhaps better than TU Chamber System



Before



After

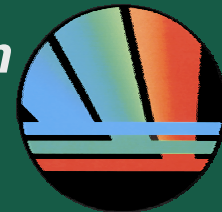






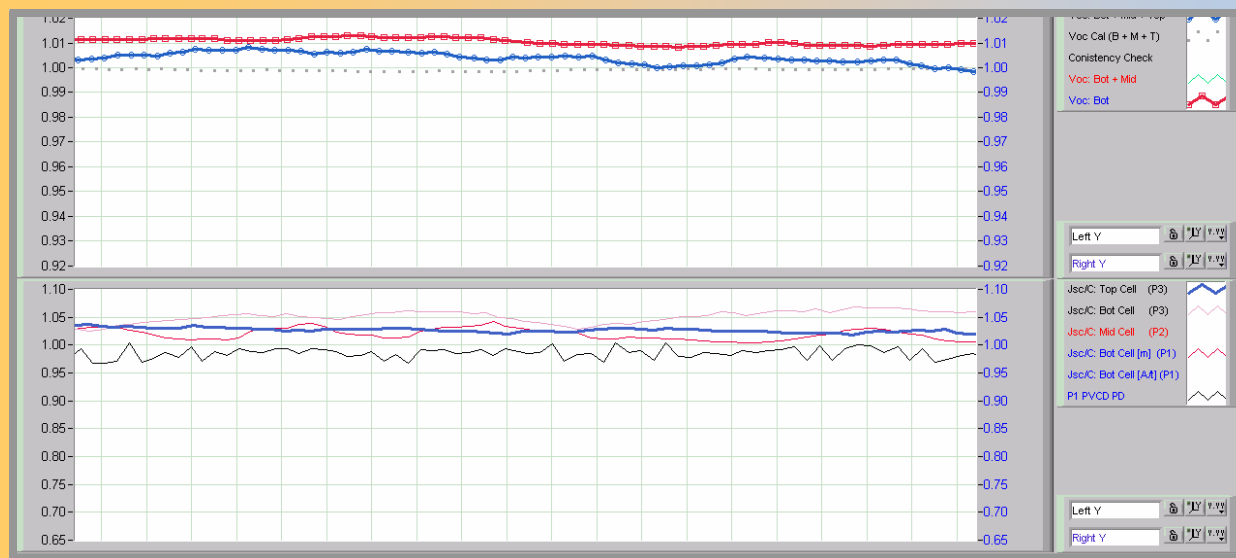
# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems



### Task 2: Component Cell PVCD

#### Summary



S/N been improved by about a factor of 10,000

Still Tweaking

All work can be applied to next generation system for the  
[Bottom+Middle] PVCD

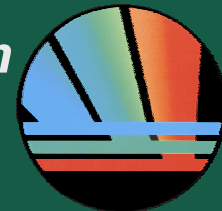
Clear mechanical improvements identified

S/N and stability appear adequate for envisioned program of  
Continuous Online Optimization – **the ultimate goal**



# ***ECD and United Solar PV Manufacturing R&D Program***

## ***Comprehensive On-Line Closed-Loop Diagnostic Systems***



### ***Task 3: Plasma Diagnostics***

#### **TASK 3: Plasma Diagnostics**

-- **Scott Jones**, Greg DeMaggio, and Tim Laarman (ECD)

##### **Milestones**

- |                  |                 |  |
|------------------|-----------------|--|
| <b>Complete</b>  | <b>m-1.0.3</b>  | <b>Initial installation of plasma monitoring sensors in pilot deposition machine.</b>    |
| <b>Complete</b>  | <b>m-1.1.3.</b> | <b>Complete installation of plasma monitoring sensors in pilot deposition machine.</b>   |
| <b>Complete</b>  | <b>m-1.2.2</b>  | <b>Initial characterization of plasmas created at 1 Å/s in pilot deposition machine.</b> |
| <b>~ 1 month</b> | <b>m-1.4.3</b>  | <b>Complete characterization of plasmas created at 1 Å/sec in pilot chamber.</b>         |
| <b>~ 1 month</b> | <b>m-1.4.4</b>  | <b>Complete the Phase I portion of the effort under Task 3.</b>                          |

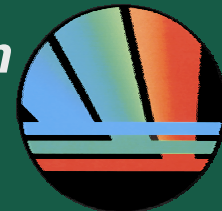
##### **Deliverables**

- |                  |                |   |
|------------------|----------------|---|
| <b>~ 1 month</b> | <b>D-1.4.1</b> | <b>Summary report of characterization studies of plasmas at 1 Å/sec in pilot deposition machine</b> |
|------------------|----------------|---|



# ***ECD and United Solar PV Manufacturing R&D Program***

## ***Comprehensive On-Line Closed-Loop Diagnostic Systems***



### ***Task 3: Plasma Diagnostics***

#### **Diagnostic Systems –**

##### **Plasma Emission Spectrometer –**

Hardware

Can we discern differences between plasma characteristics at low and high deposition rates?

In intrinsic-type deposition conditions?

In p-type deposition conditions?

##### **Particle (powder) Detection –**

Powder is BAD –

Reduces deposition rates

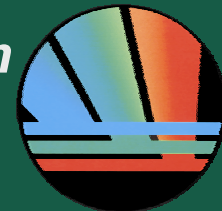
Can lead to shunts in final product

Would any of these techniques be applicable to operations?



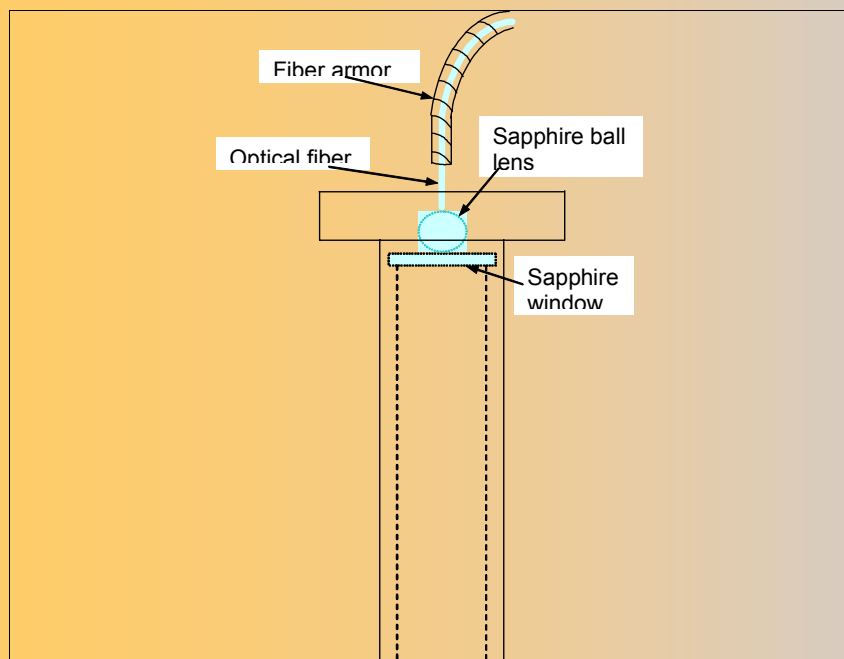
# **ECD and United Solar PV Manufacturing R&D Program**

## **Comprehensive On-Line Closed-Loop Diagnostic Systems**



### **Task 3: Plasma Diagnostics**

#### **Plasma Emission Spectrometer – Hardware**



#### **Design Challenges**

High Temperatures  
Deposition onto Optics  
UHV-Compatible

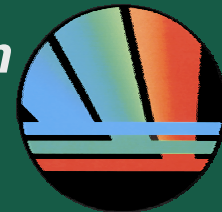
Ocean Optics 2000 USB Spectrometer





# ECD and United Solar PV Manufacturing R&D Program

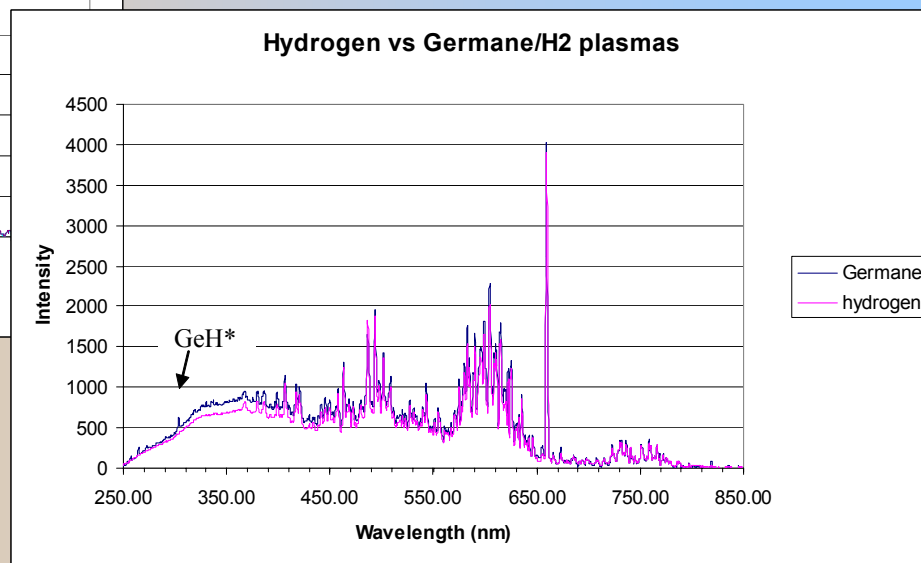
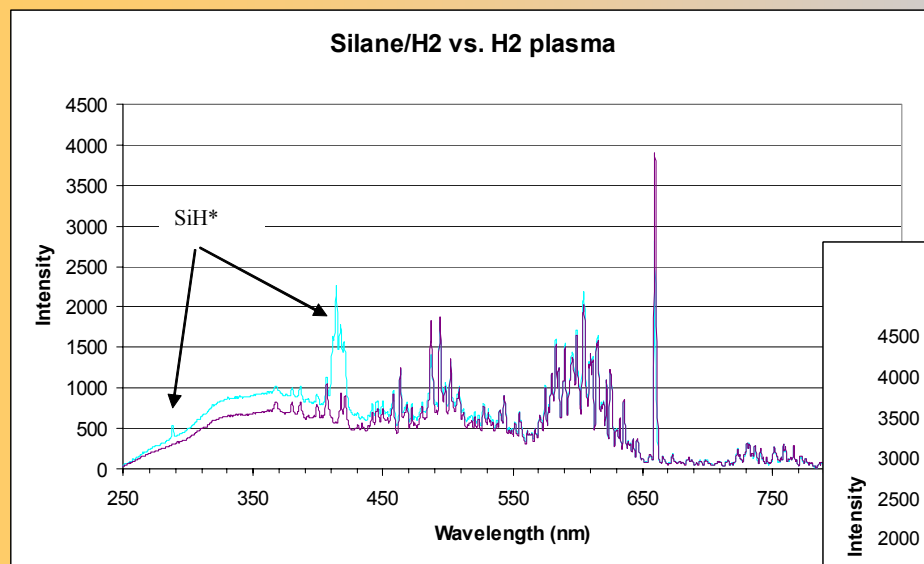
## Comprehensive On-Line Closed-Loop Diagnostic Systems



### Task 3: Plasma Diagnostics

**Plasma Emission Spectrometer –**  
Intrinsic-type deposition conditions

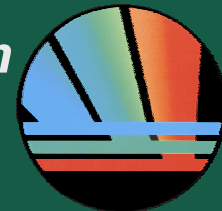
Have Looked at Si:H and Ge:H  
plasmas





# ECD and United Solar PV Manufacturing R&D Program

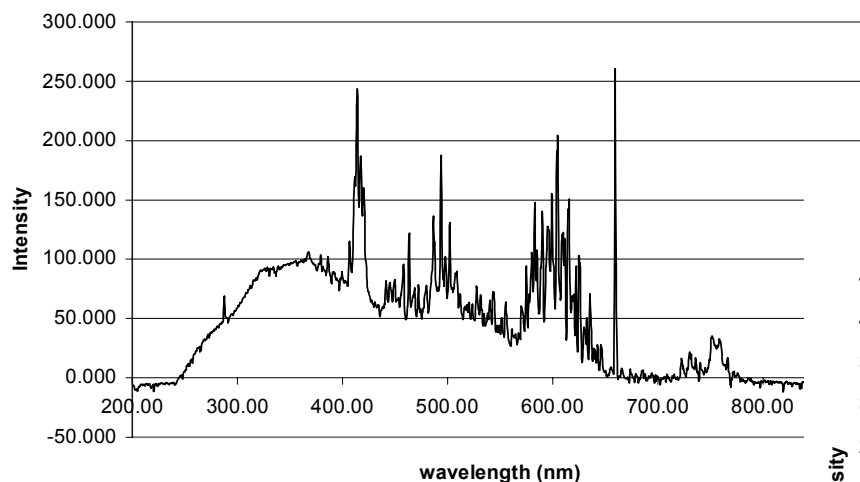
## Comprehensive On-Line Closed-Loop Diagnostic Systems



### Task 3: Plasma Diagnostics

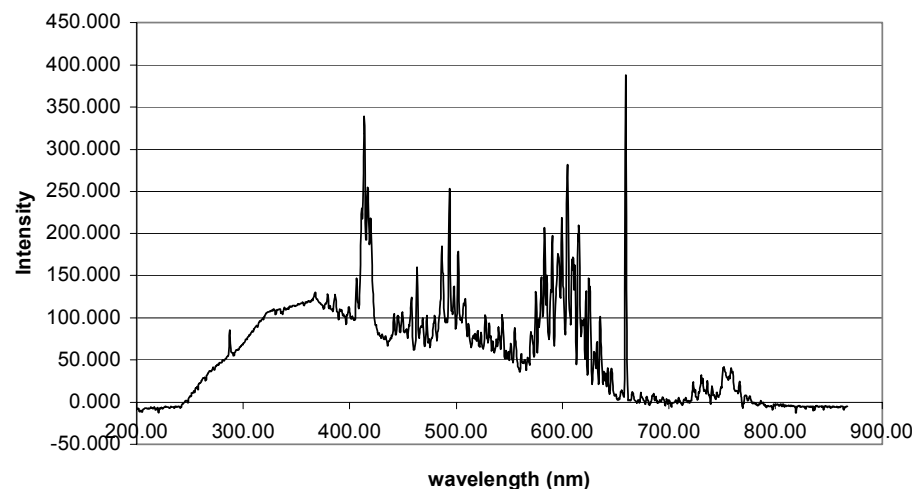
#### Plasma Emission Spectrometer – Intrinsic-type deposition conditions

OES emission spectra



Low (1 Å/s) and High (3 Å/s) H<sub>2</sub>  
Dilution and Deposition Rates

OES emission spectra

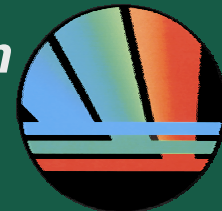


Operations – perhaps simple,  
rugged, low-cost PEM's at SiH\*,  
GeH\* and H peaks?



# *ECD and United Solar PV Manufacturing R&D Program*

## *Comprehensive On-Line Closed-Loop Diagnostic Systems*



### *Task 3: Plasma Diagnostics*

**Plasma Emission Spectrometer –**  
p-type deposition conditions

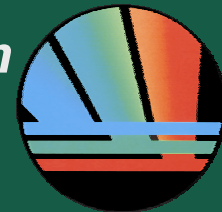
p-type deposition hardware currently  
being installed





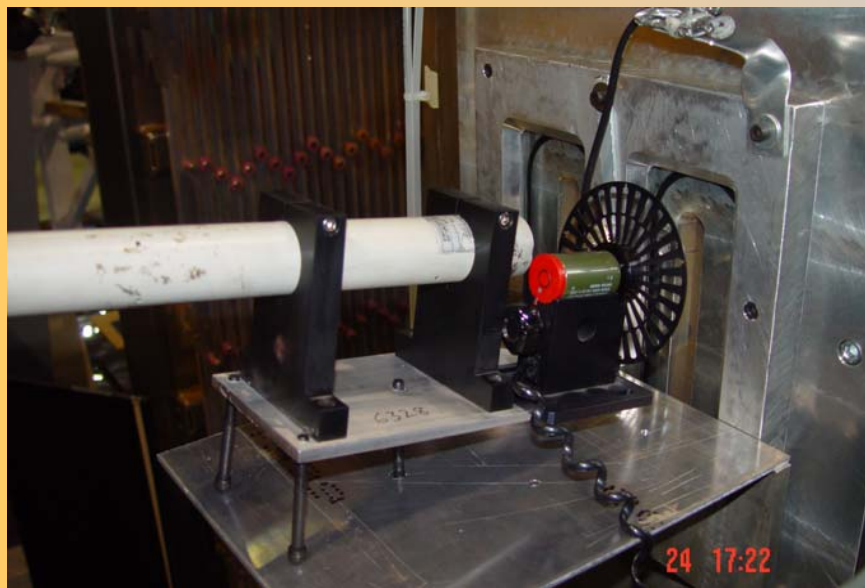
# **ECD and United Solar PV Manufacturing R&D Program**

## **Comprehensive On-Line Closed-Loop Diagnostic Systems**



### **Task 3: Plasma Diagnostics**

#### **Laser Particle Detection Hardware**



Have observed small response when  
operating with excessive powder  
formation conditions

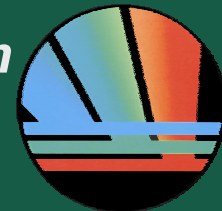






# **ECD and United Solar PV Manufacturing R&D Program**

## **Comprehensive On-Line Closed-Loop Diagnostic Systems**



### **Task 4: Yield Improvements: Substrate Cleaning**

#### **TASK 4: Yield Improvement: Substrate Cleaning and Monitoring**

Greg DeMaggio (ECD), Gary Di Dio, Peter Nam, Wai Kei Chan (United Solar)

##### **Milestones**

Complete	m-1.0.4	Complete setup of OSEE Surface Quality Monitor on United Solar wash line.
Complete	m-1.1.4	Complete initial baseline characterization of surface monitor. Correlation with substrate cleaning parameters.
Complete	m-1.2.3	Complete initial investigation of plasma cleaning parameters and correlation with QA/QC data.
~ month	m-1.4.5	Complete evaluation of effectiveness of plasma cleaning vs. chemical cleaning.
In Progress	m-1.4.6	Complete evaluation of on-line techniques for measuring substrate cleanliness.
	m-1.4.7	Complete the Phase I portion of the effort under Task 4.

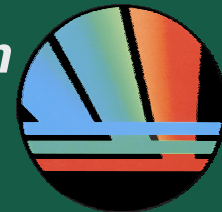
##### **Deliverables**

Complete	D-1.0.2	Report describing surface quality monitor on substrate wash line.
~ month	D-1.4.2	Report summarizing of plasma vs. chemical cleaning, and correlation with offline QA/QC
~ monty	D-1.4.3	Report summarizing data from cleanliness monitoring and correlation with offline QA/QC



# ***ECD and United Solar PV Manufacturing R&D Program***

## ***Comprehensive On-Line Closed-Loop Diagnostic Systems***



### ***Task 4: Yield Improvements: Substrate Cleaning***

#### ***Diagnostics to Monitor Surface Cleanliness in Washing Machine***

Installation of Diagnostics

Measurements

Different Substrates

With Varying Wash Conditions

Initial Testing

Matrix Testing

#### ***Plasma Cleaning***

Initial Measurements

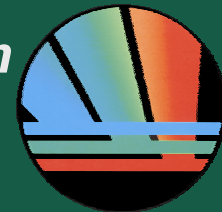
Measurements in Progress

***Success in proving Plasma Cleaning works better than Wet Chemical Cleaning would allow us to eliminate one of 4 roll-to-roll Front End Processors – this is our ultimate goal.***



# **ECD and United Solar PV Manufacturing R&D Program**

## **Comprehensive On-Line Closed-Loop Diagnostic Systems**



### **Task 4: Yield Improvements: Substrate Cleaning**

#### **Diagnostics to Monitor Surface Cleanliness in Washing Machine** **Installation of Diagnostics**



**OSEE – Optically Stimulated Electron Emission  
Instrument-Substrate distance critical  
A couple iterations on mounting**

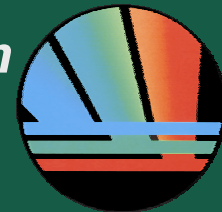




# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems

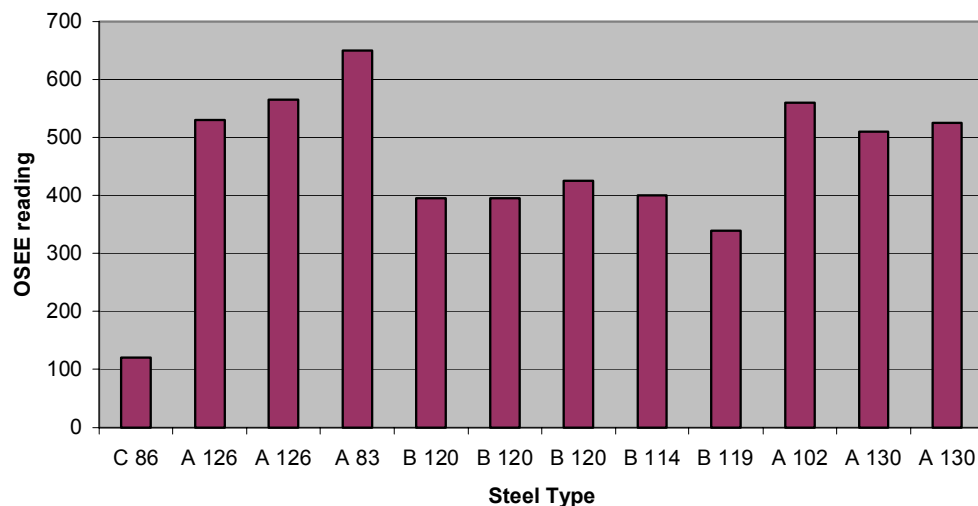
### Task 4: Yield Improvements: Substrate Cleaning



## Diagnostics to Monitor Surface Cleanliness in Washing Machine

### Initial Tests

Average OSEE Reading for Different Steels (Online)

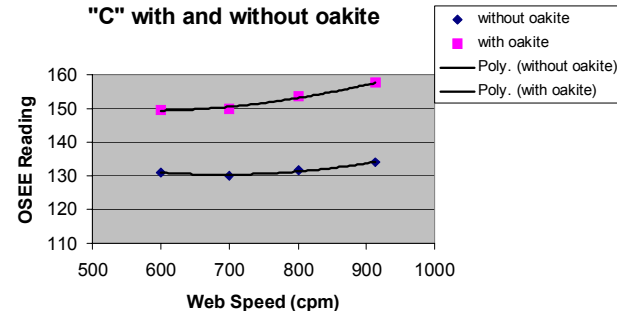


*OSEE signal found to vary significantly with different substrates – we found a correlation with surface finish – the higher the quality of the finish, the higher the OSEE signal.*

*Absolute surface contamination measurements not possible.*

*Also found correlations with web speed – system may still provide relative measurements to assess cleaning conditions.*

"C" with and without oakite

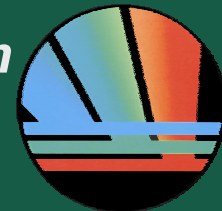






# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems



### Task 4: Yield Improvements: Substrate Cleaning

## Diagnostics to Monitor Surface Cleanliness in Washing Machine

### Experimental Matrix Relative Measurements

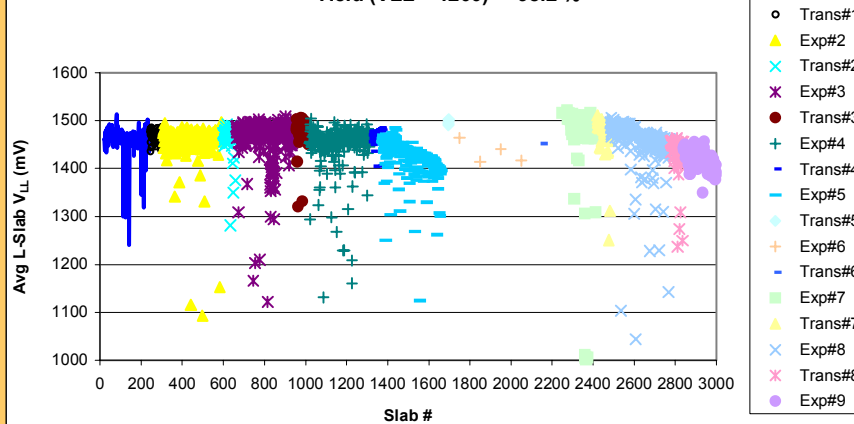
Test #	PH	Speed	OSEE reading		Difference
			PO	TU	
1	pH 8.5	600cm/min	352.7	434.8	23.3%
2		750cm/min	368.7	441.2	19.7%
3		914cm/min	370.0	433.9	17.3%
4	pH 10	600cm/min	375.5	488.3	30.0%
5		750cm/min	384.3	475.9	23.8%
6		914cm/min	391.1	475.0	21.5%
7	pH 12.3	600cm/min	397.7	665.5	67.4%
8		750cm/min	399.4	630.6	57.9%
9		914cm/min	407.1	609.2	49.6%

### Results –

*Increased Detergent Level (pH) increases OSEE signal –*

*However, no indication that OSEE signal correlates with degree of shunts in final product.*

5MW 1767 Initial VLL vs Slab#.  
Yield (VLL > 1200) = 98.2 %



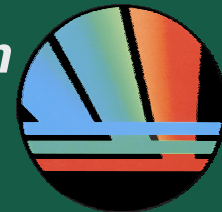
Test #	PH	Speed	OSEE reading		Difference	Average
			PO	TU		V <sub>LL</sub>
1	6.22	914cm/min	332.00	355.00	23.00	1.48
4	7.50	914cm/min	327.00	337.00	10.00	1.45
2	11.38	914cm/min	329.00	454.00	125.00	1.52
3	11.94	914cm/min	327.00	498.00	171.00	1.49



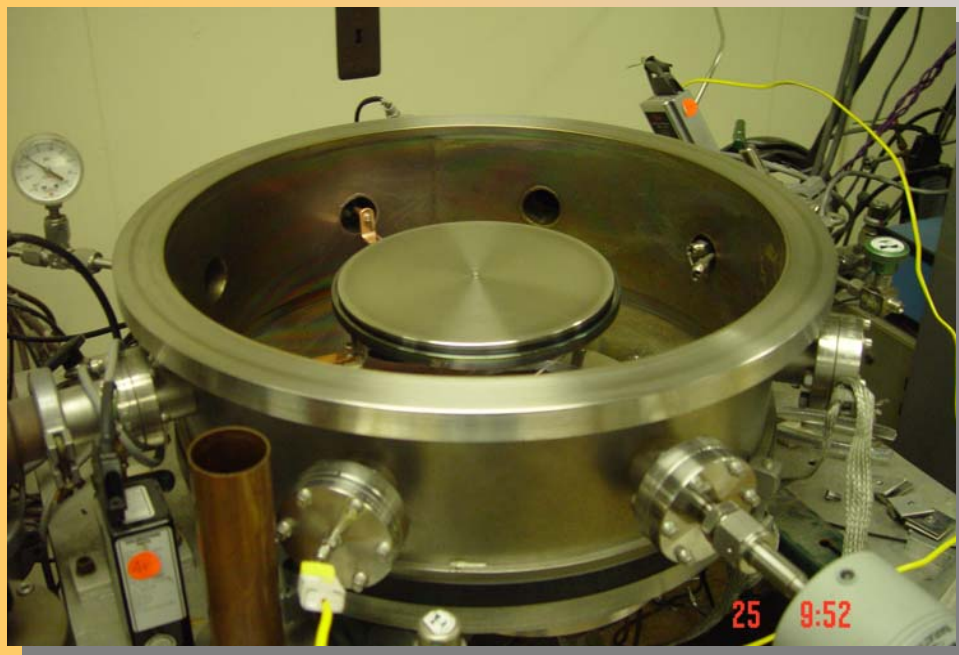
# ***ECD and United Solar PV Manufacturing R&D Program***

## ***Comprehensive On-Line Closed-Loop Diagnostic Systems***

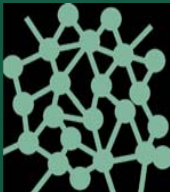
### ***Task 4: Yield Improvements: Substrate Cleaning***



#### ***Plasma Cleaning --***



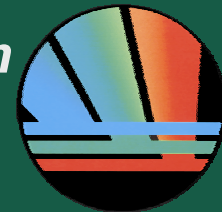
***Need to test offline before testing in production machines***



# ECD and United Solar PV Manufacturing R&D Program

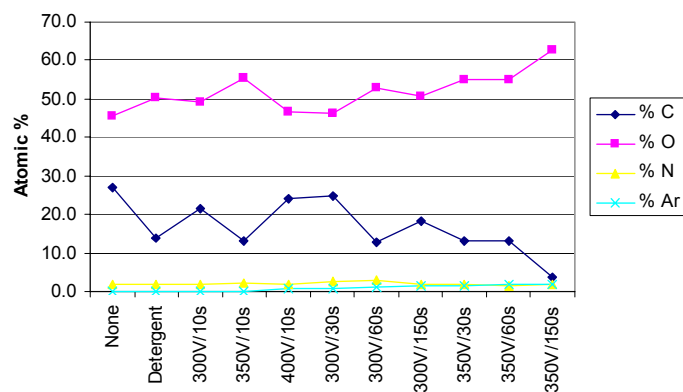
## Comprehensive On-Line Closed-Loop Diagnostic Systems

### Task 4: Yield Improvements: Substrate Cleaning



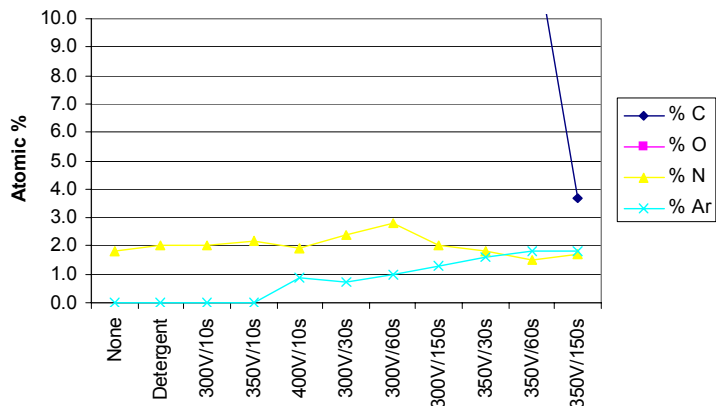
## Plasma Cleaning --

Level of Surface Contaminants Following Treatment

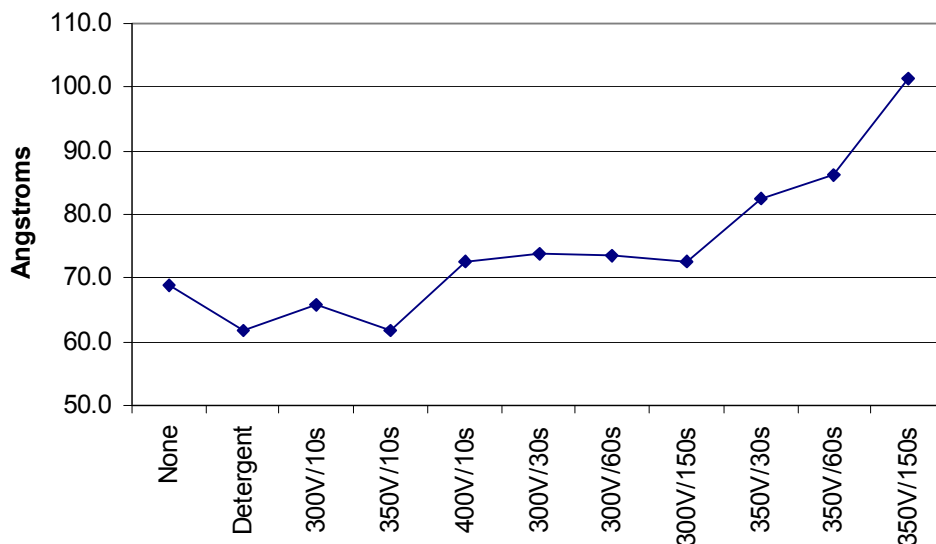


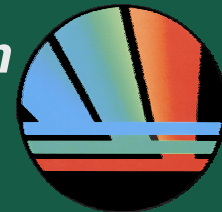
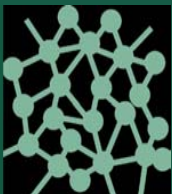
*Comparisons between chemically-cleaned and plasma-cleaned substrates*

Level of Surface Contaminants Following Treatment



Thickness of Surface Oxide Following Treatment



**Task 4: Yield Improvements: Substrate Cleaning****Plasma Cleaning --**

*In Progress –*

*Definitive Test –*

*Apply oil to surface of substrates  
Clean in Production WM and with Plasma Cleaner,  
varying conditions*

*Does plasma cleaning provide same degree of oil cleanup  
as does chemical cleaning?*

*Can we then demonstrate cleaning this oil residue in the  
production BR machine*

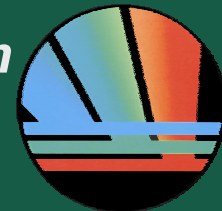
*Then – trial test of substrate using plasma cleaning in BR  
machine w/o chemical cleaning*





# ECD and United Solar PV Manufacturing R&D Program

## Comprehensive On-Line Closed-Loop Diagnostic Systems



### Conclusions

We are grateful for NREL's support.

Exponential growth

– it's an interesting thing --

*To see a World in a Grain of Sand  
And a Heaven in a Wild Flower  
Hold Infinity in the palm of your hand  
And Eternity in an hour*

*William Blake, Auguries of Innocence*

